

MAMBO III

Monolithic **A**ctive Pixel **M**atrix with **B**inary **C**ounters

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Presentation Outline

- ✦ Applications
- ✦ Previous Work: MAMBO II
 - ✦ Design
 - ✦ Results
- ✦ MAMBO III development
 - ✦ Goals
 - ✦ Schematic
 - ✦ Layout
- ✦ T-Micro (ZyCube) 3D Integration
- ✦ MAMBO IV: Future work

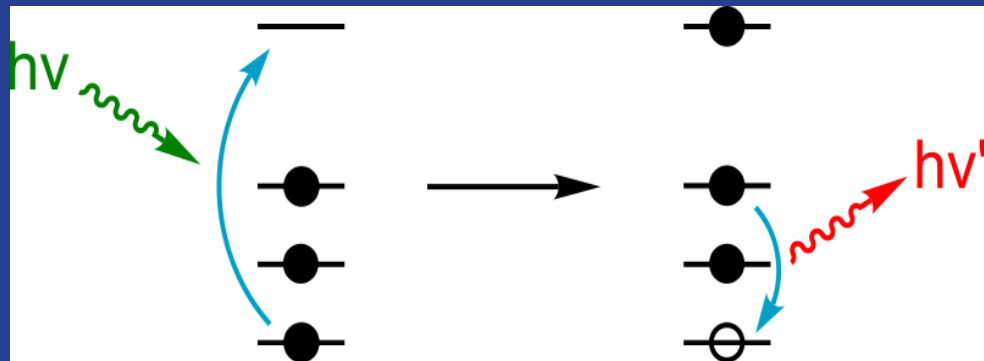
POSSIBLE APPLICATIONS

Possible applications

- ✦ Low energy applications up to 12kEv

E.g.

- ✦ X-ray autoradiography
- ✦ Fluorescence X-ray spectroscopy



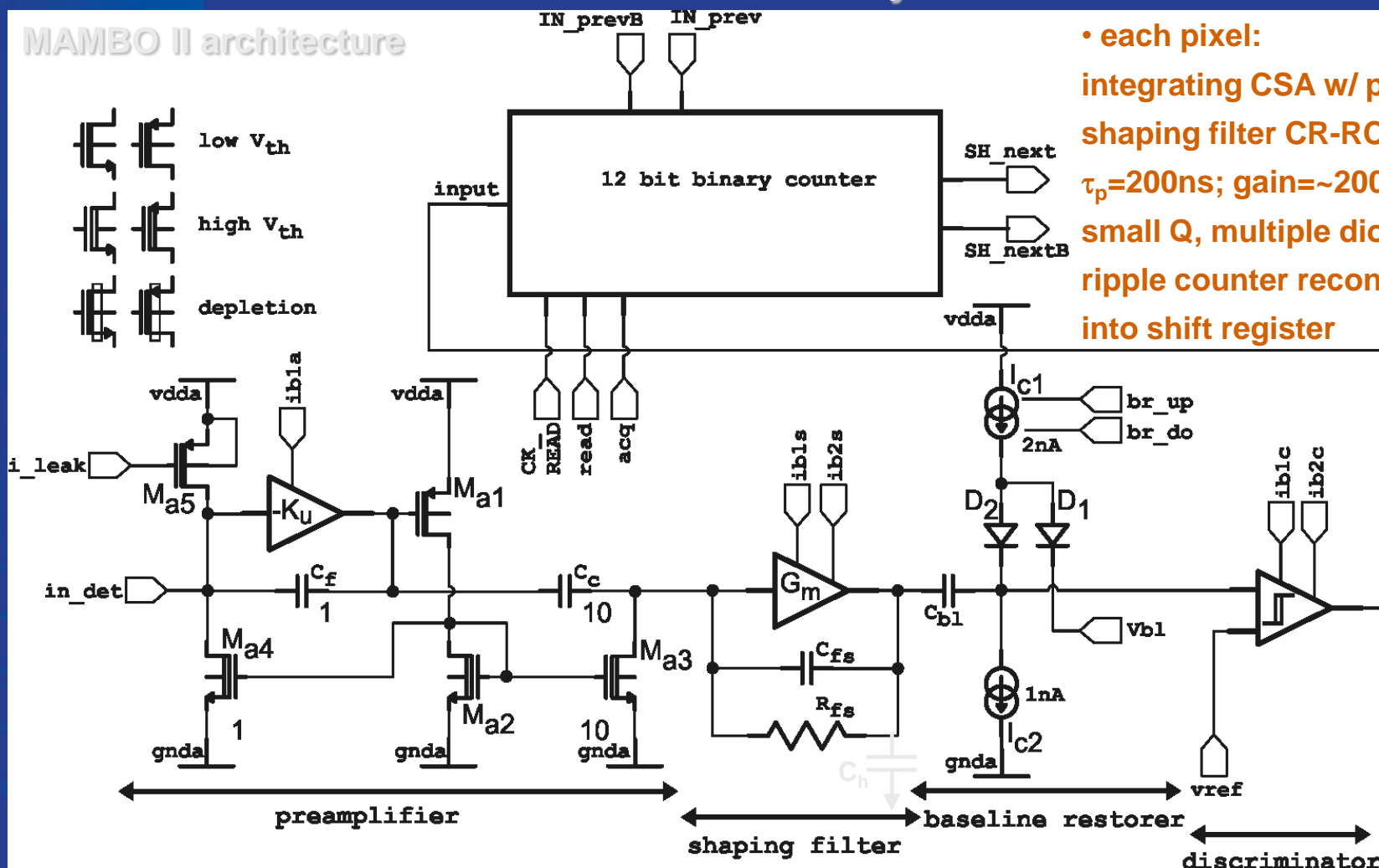
PREVIOUS WORK

MAMBO2

Design details of pixel imaging detector „MAMBO“

MAMBO = **M**onolithic **A**ctive **P**ixel **M**atrix with **B**inary **C**ounters

MAMBO II architecture



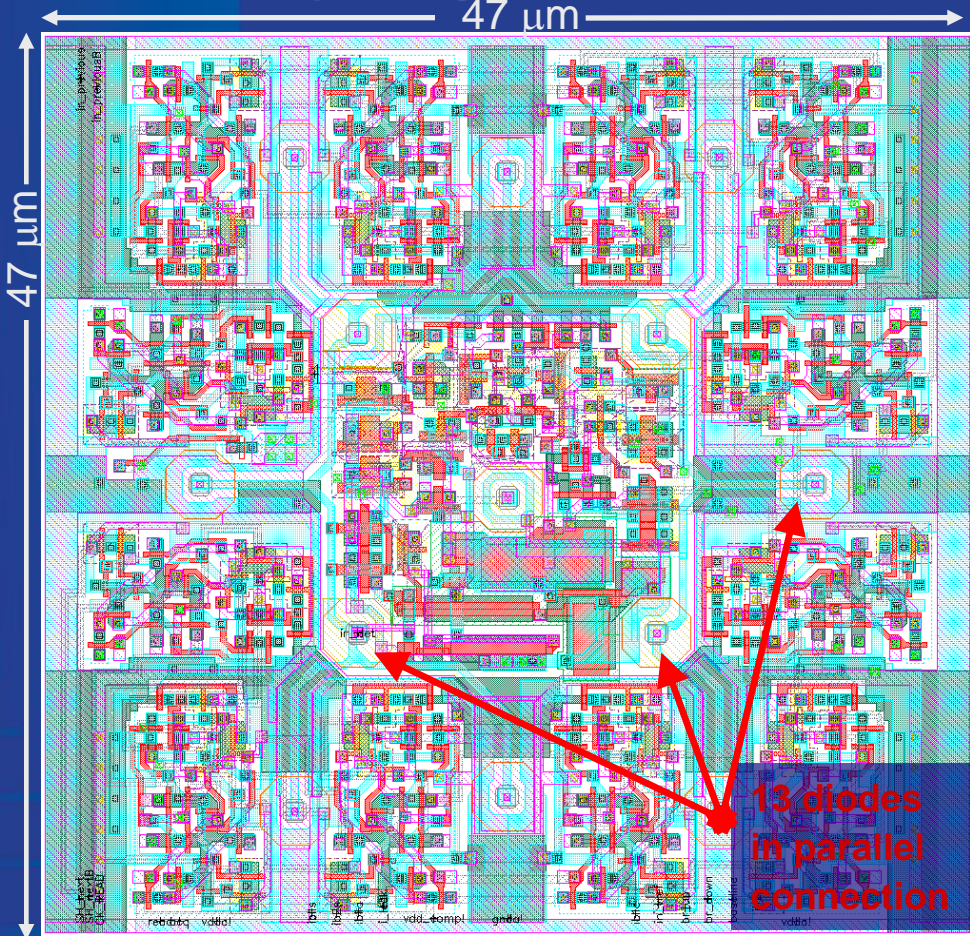
- each pixel:
 - integrating CSA w/ p-z network,
 - shaping filter CR-RC² with $\tau_p=200\text{ns}$;
 - gain= $\sim 200 \mu\text{V}/e^-$ for small Q,
 - multiple diodes/pixel,
 - ripple counter reconfigurable into shift register

• compact design excluding use of physical resistors

MAMBO2: PREVIOUS WORK....

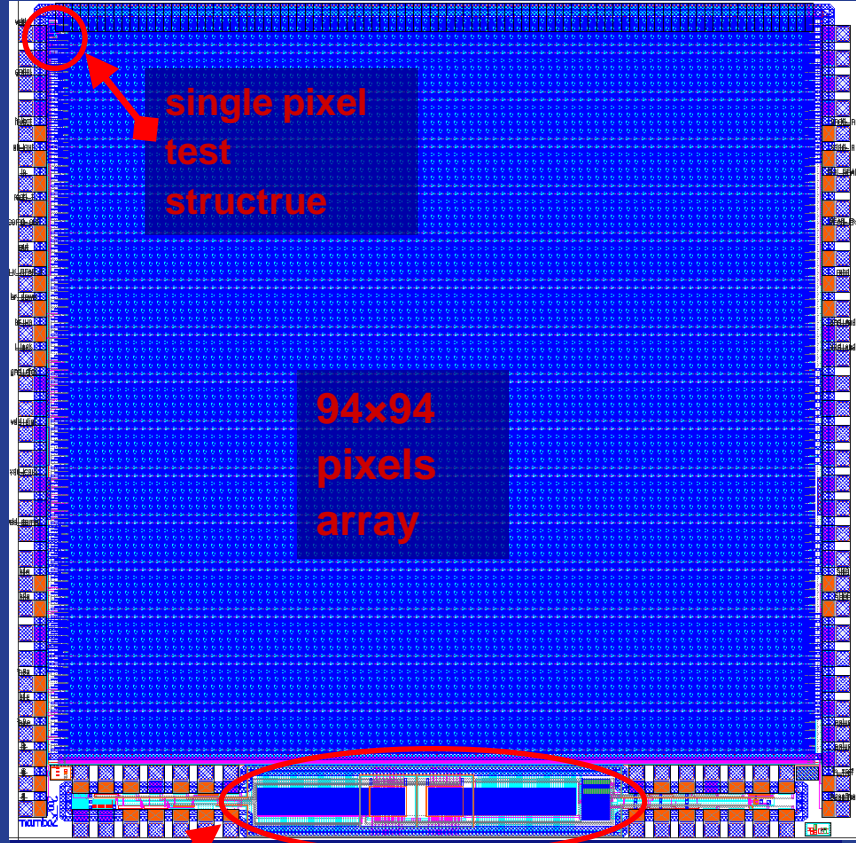
Design details of pixel imaging detector „MAMBO“

▶▶ MAMBO II pixel layout



Multiple p-taps (used as signal electrodes) present per pixel for reduction of shifts of threshold voltages. **Partial success:** adjustment of bias voltages and currents (referred to V_{GS}) up to several tens of mV still required for V_{back} from the range from 0 to 10V.

▶▶ MAMBO II chip layout



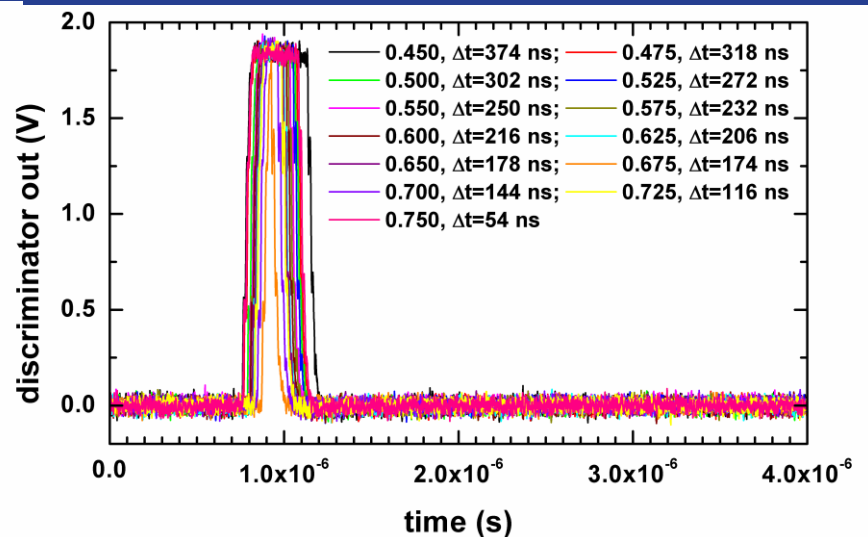
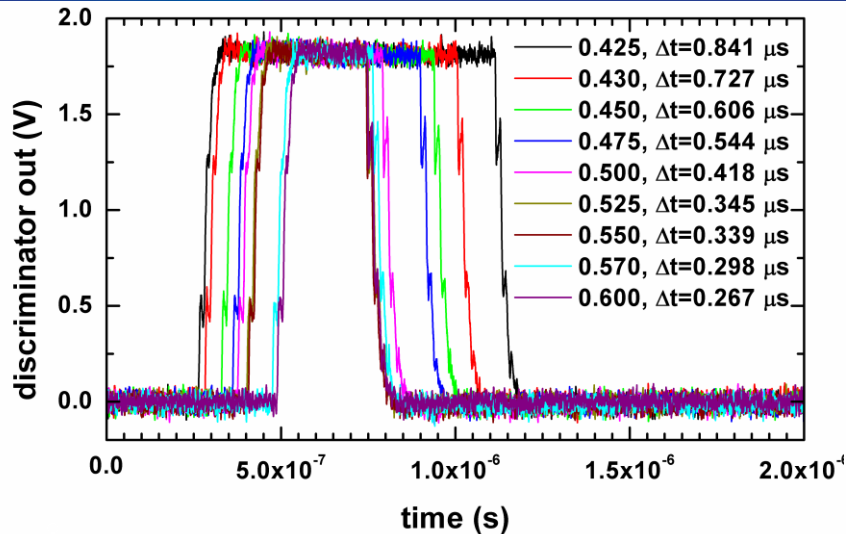
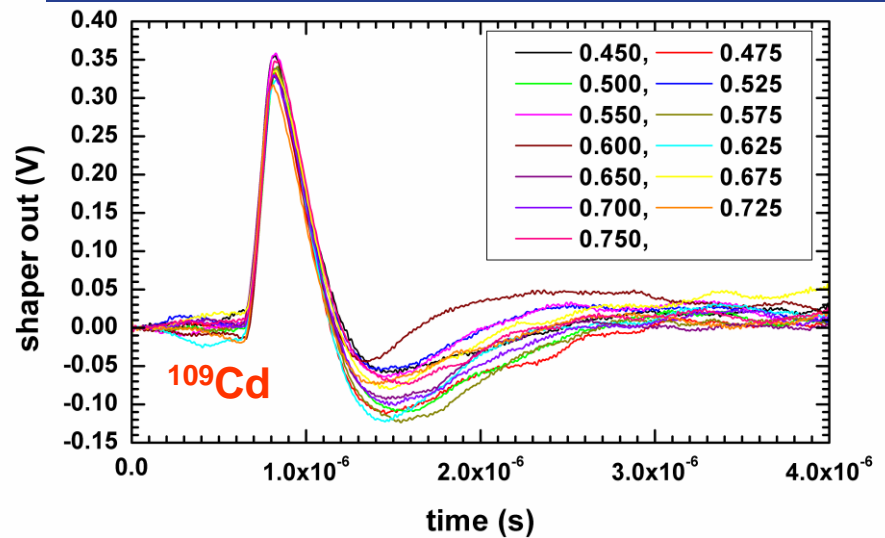
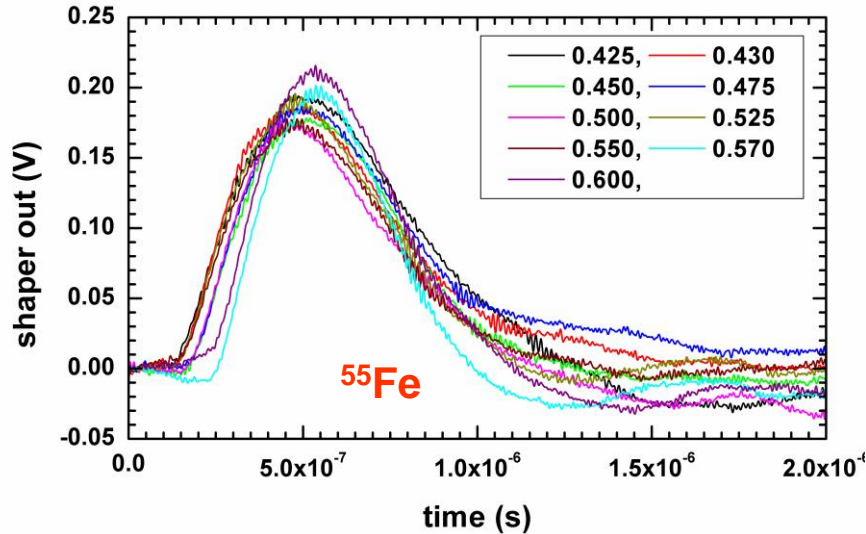
8x10 20x20 μm^2 3T pixel matrices for x-talk and test charge collection tests

Single pixel test structure is a fully functional circuit allowing monitoring: shaper output, discriminator output, counter output

Achievements, observations and investigations

MAMBO II single pixel test

Monitoring of the shaper and discriminator outputs (transient signals)



Conclusions

credo: strength of the SOI monolithic active pixel technology is integration of whole processing circuitry directly into 'the focal plane'



- the OKI process offers enhancements: through BOX contacts and diode and ohmic implants in the substrate material for the first time in a commercial approach!



- monolithic detector structures can operate depleted for the first time successfully!



- matrices using 3T-type pixels can successfully be built (NMOS/PMOS switches may be used); – some progress but not too much beyond bulk MAPS.



- mutual influence of CMOS circuitry and the detector is affecting designs of more advanced circuits for imaging.



- FD-SOI represents challenges for precise analog circuits, one would prefer different flavor!

- the properties of the substrate material and how it is depleted is far from being understood. The depletion may depend on transient and statically hold voltage states in the CMOS circuitry!

- observed high sensitivity to irradiation; overnight exposure under $100 \mu\text{Ci } ^{109}\text{Cd}$ under full operation causes $\sim 100 \text{ mV}$ voltage levels shifts.

- the process must be enhanced.

The first priorities are to separate substrate and CMOS circuitry

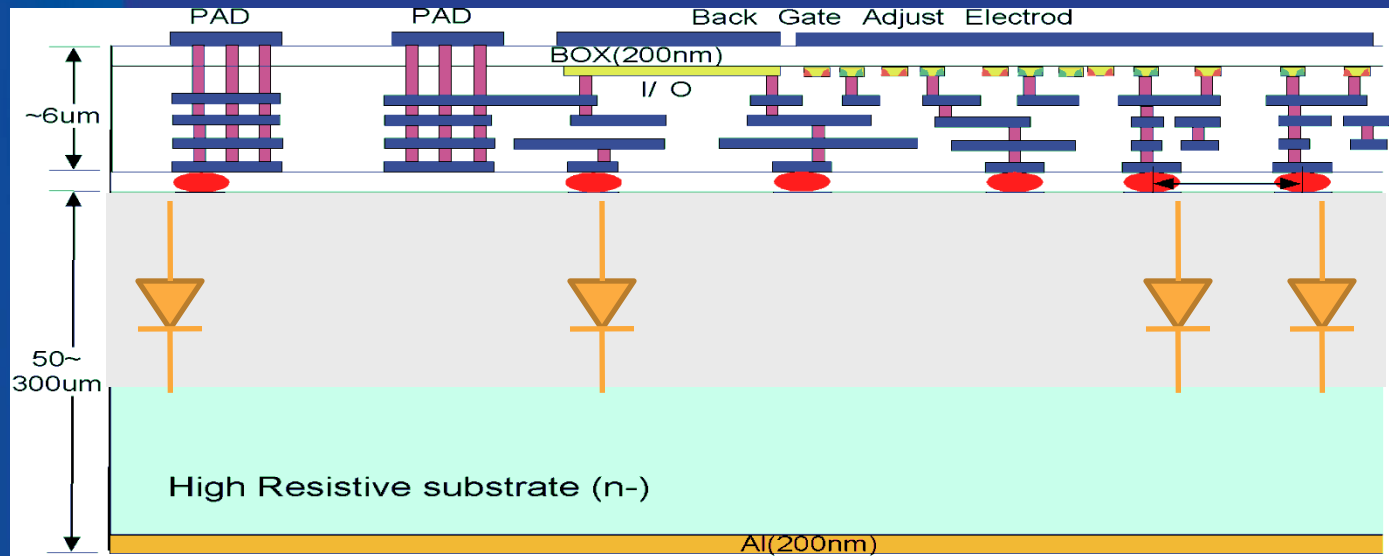


MAMBO III

Goals

- ✦ R&D
- ✦ Detector and electronics on different layers (to avoid coupling)
- ✦ Diodes with PPLUS with BPW to reduce leakage
- ✦ Diode of the same size as the pixel to obtain parallel electric field in active volume, and avoid potential pockets
- ✦ Shielding on detector layer
- ✦ Possibility of changing gated diode voltage to enhance performance of the diode
- ✦ Explore 3D IC technology with T-Micro

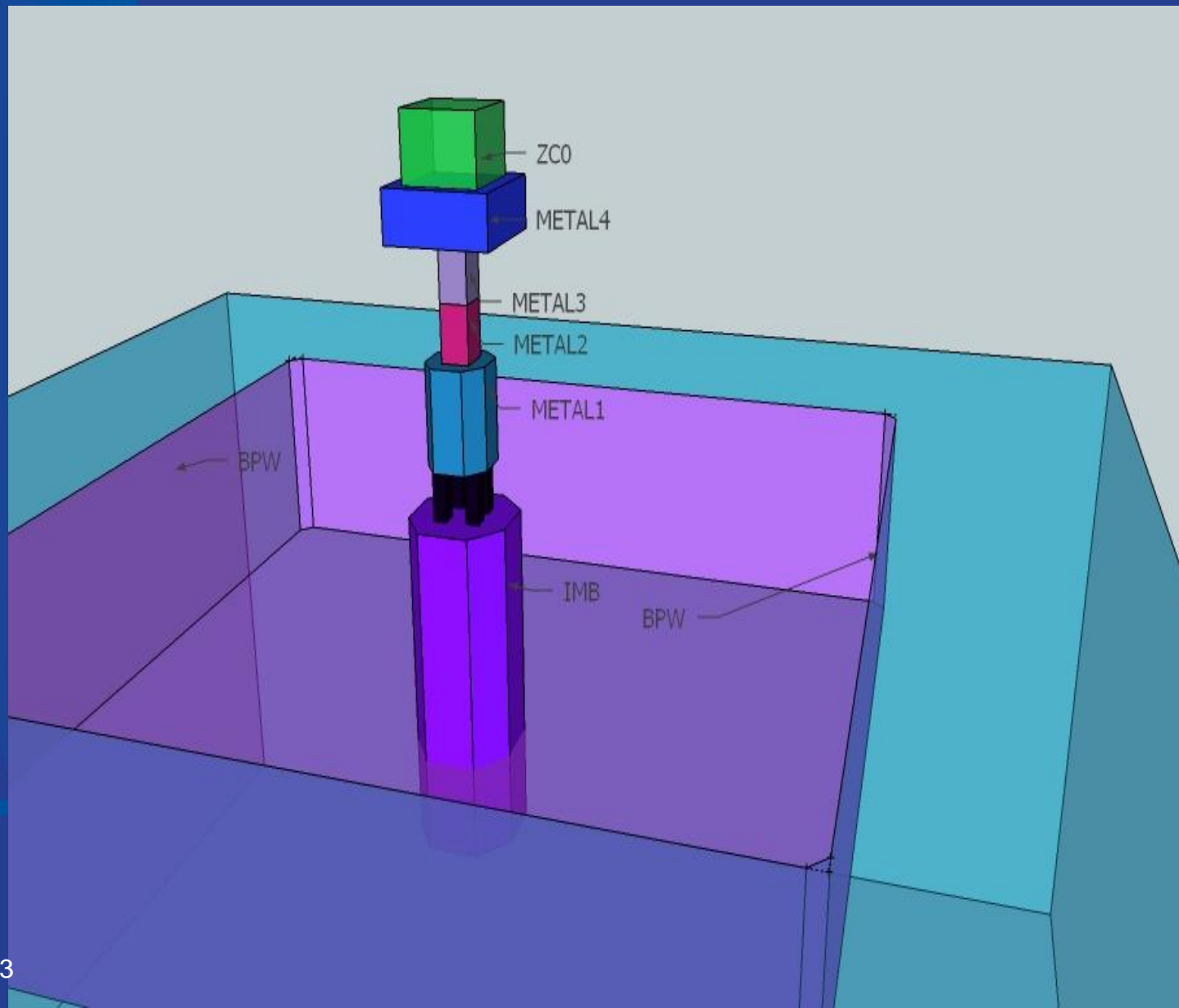
3D : MAMBO 3



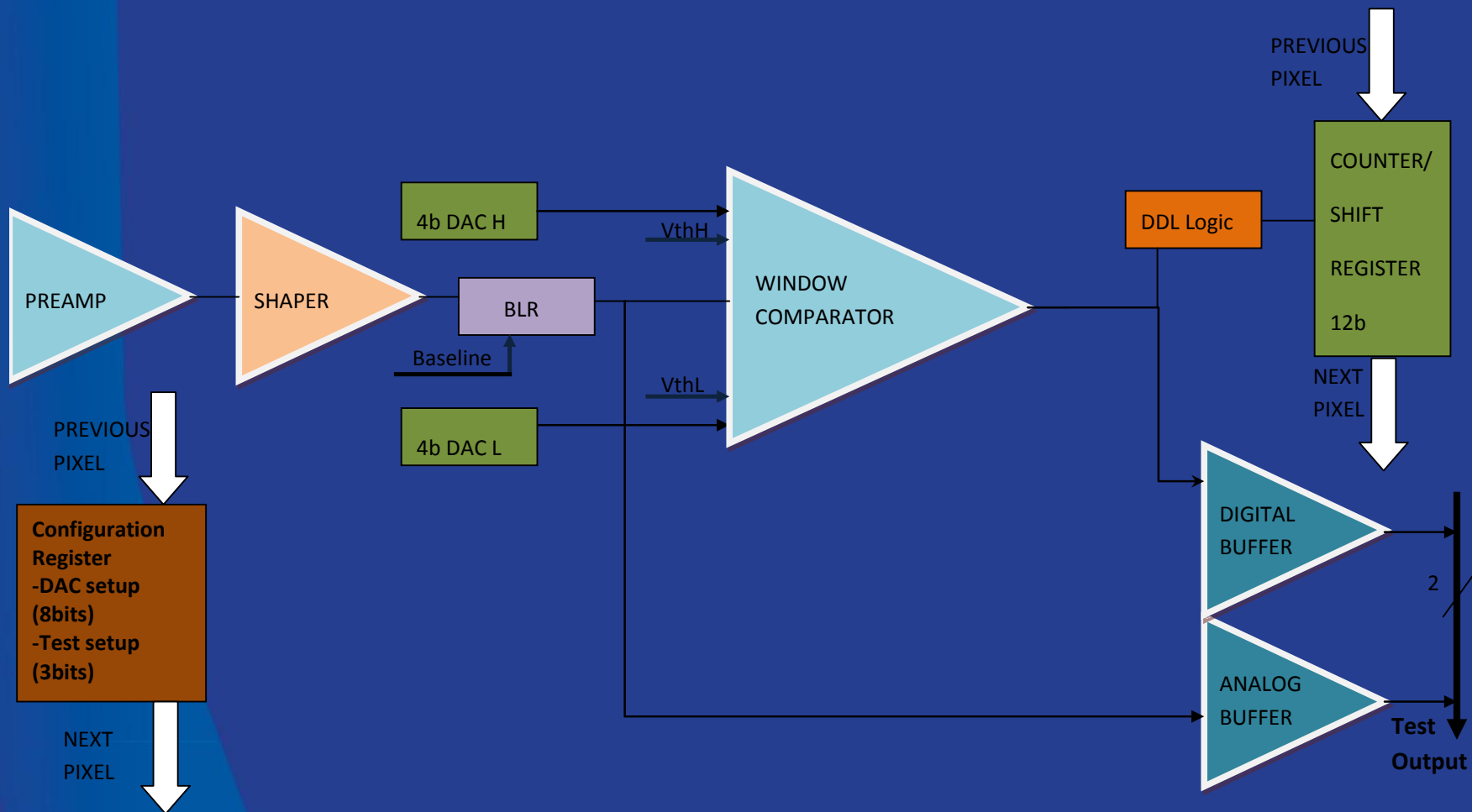
MAMBO 3
top ASIC

MAMBO 3
bottom
ASIC

3D Model: Diode (Bottom Pixel)



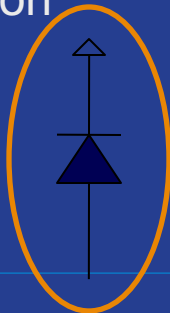
Top ASIC: PIXEL Design



Preamplifier

- Regulated Cascode
- Leakage current compensation
- 1.7fF I/P test capacitance

Protection diode



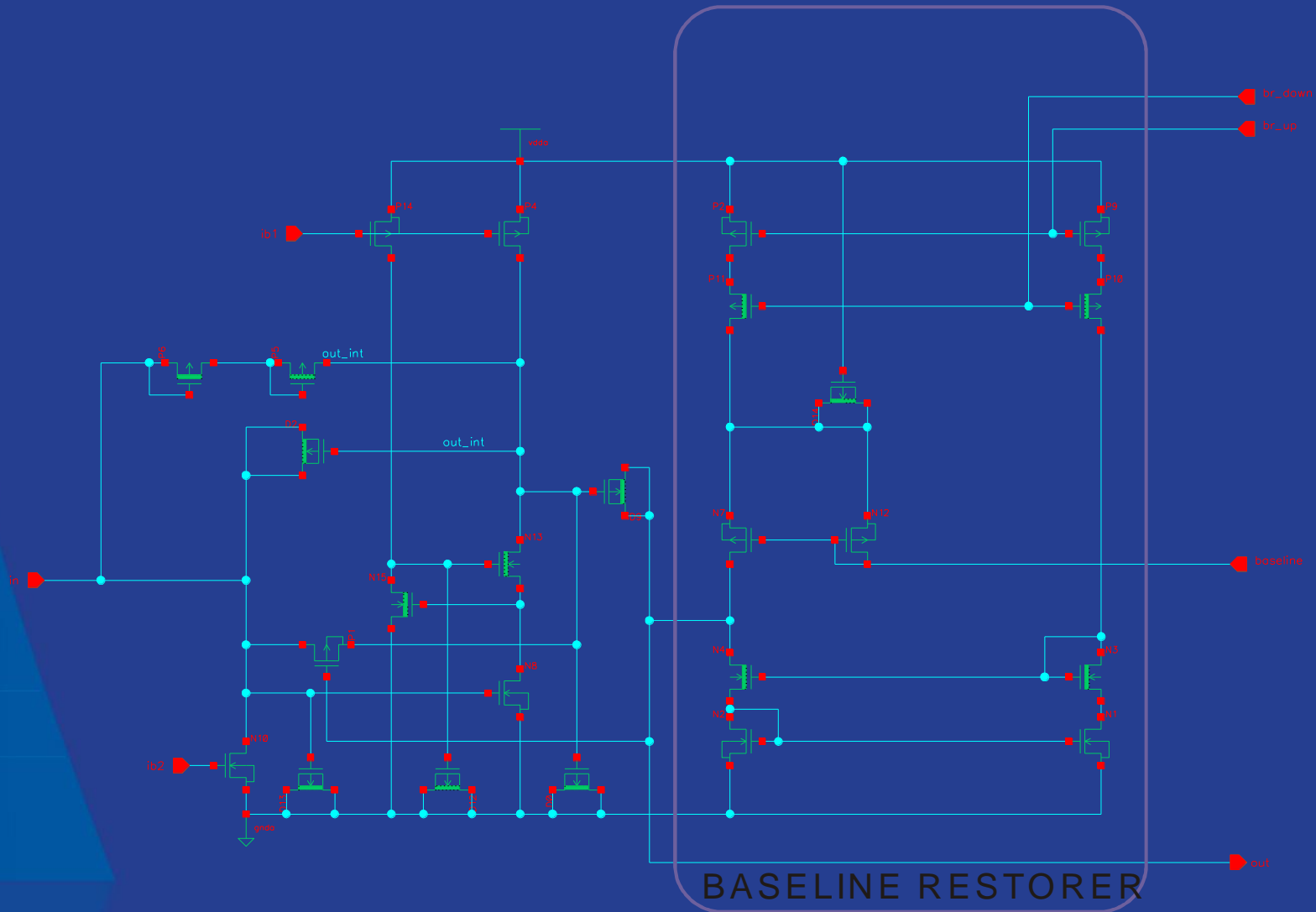
Feedback Capacitor

Coupling Capacitor

Test Setup

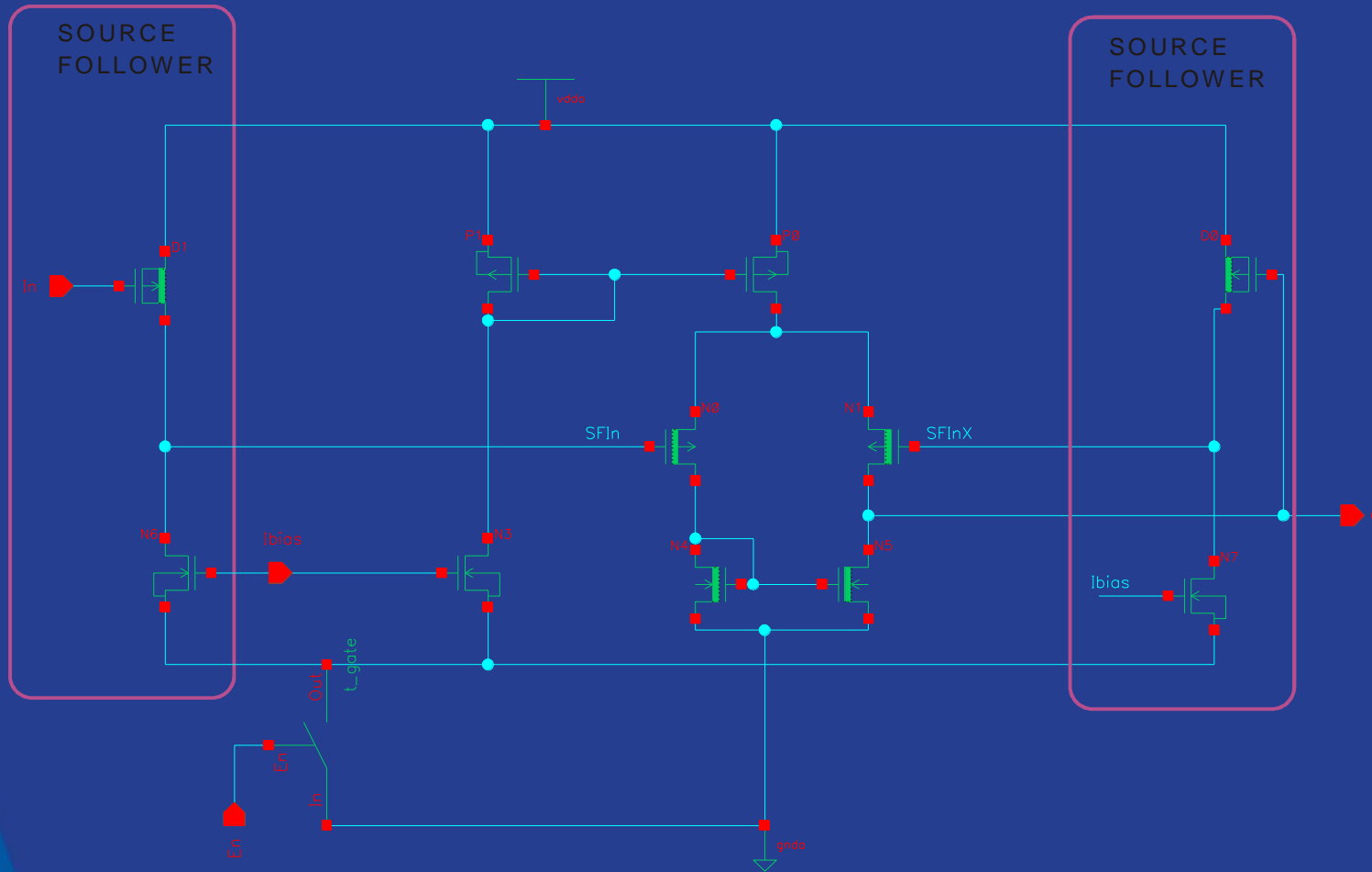
$C_{fs}=5\text{fF}$, $G_m=6.5\mu\text{S}$, $R_{fs}=28\text{M}\Omega$, $C_h=25\text{fF}$,
 $C_c=35\text{fF}$

Shaper and Baseline Restorer



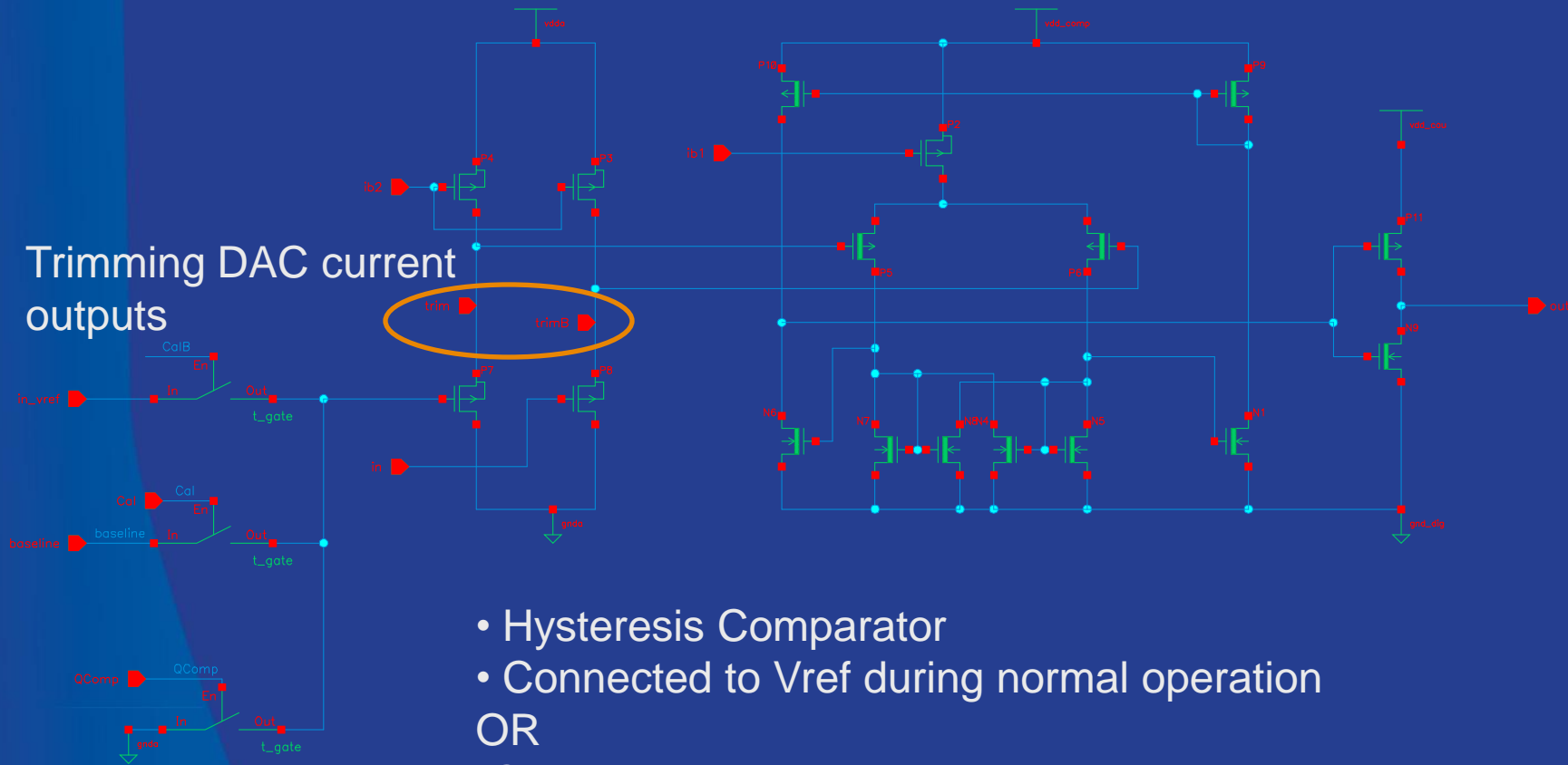
Analog Test Buffer

- Source Followers using Zero V_t DMOS transistors
- Single Stage amplifier
- Disconnected during normal mode of operation
- 10 μA current



Comparator

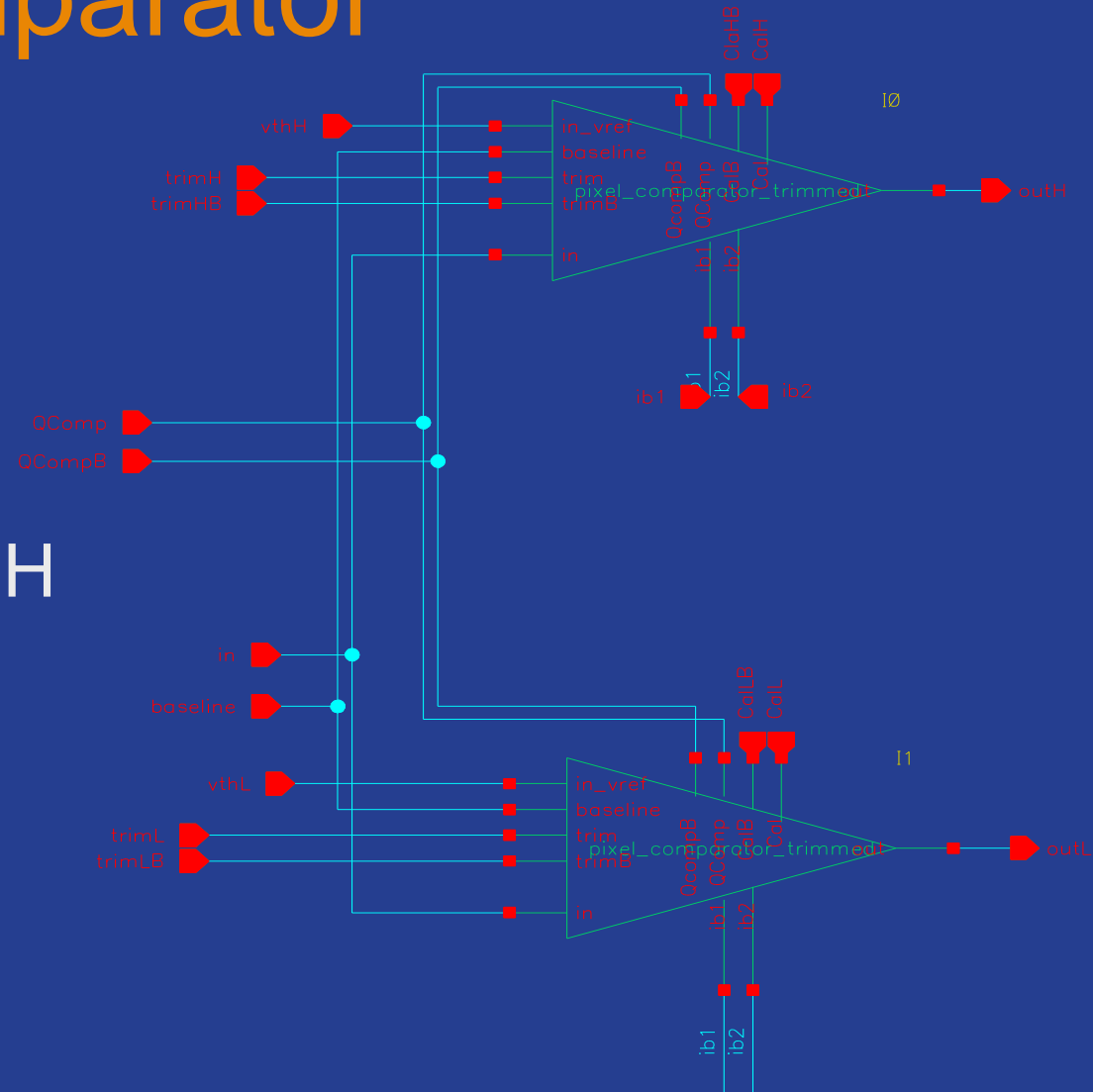
Trimming DAC current outputs



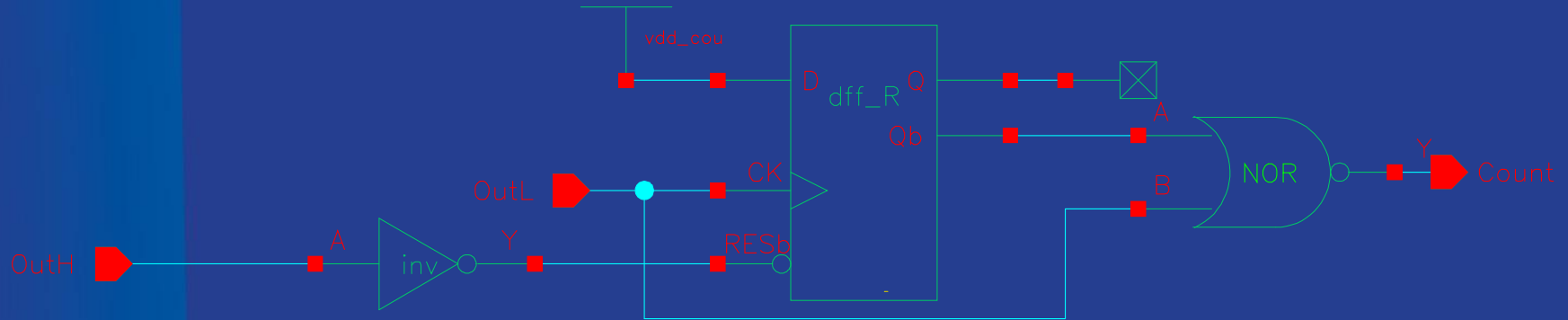
- Hysteresis Comparator
- Connected to V_{ref} during normal operation
- OR
- Connected to $baseline$ for trimming
- OR
- Connected to gnd ! when disabled

Window Comparator

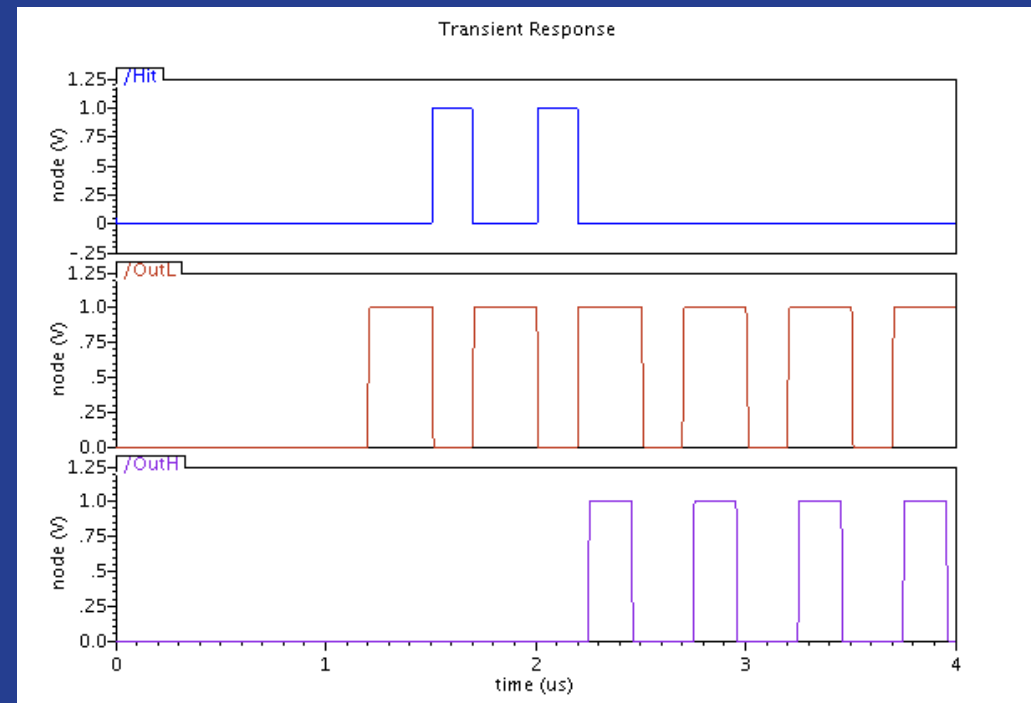
- ☀ VthL – Lower Threshold
- ☀ VthH –Upper Threshold
- ☀ $V_{thL} < \text{Signals} < V_{thH}$ is recorded as HIT
- ☀ Comparators are independently trimmed to cancel offsets



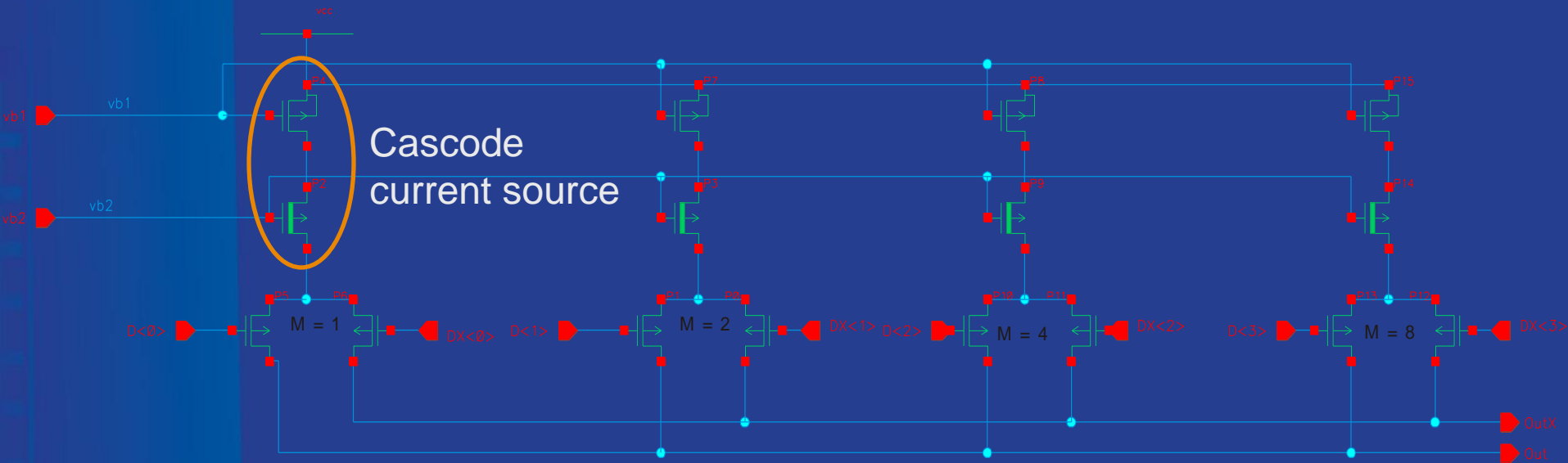
Double Discriminator Logic



- Output of the Lower Threshold comparator behaves as a clock
- Output of the Upper Threshold comparator behaves as a Reset
- When both comparators fire the hit is not counted

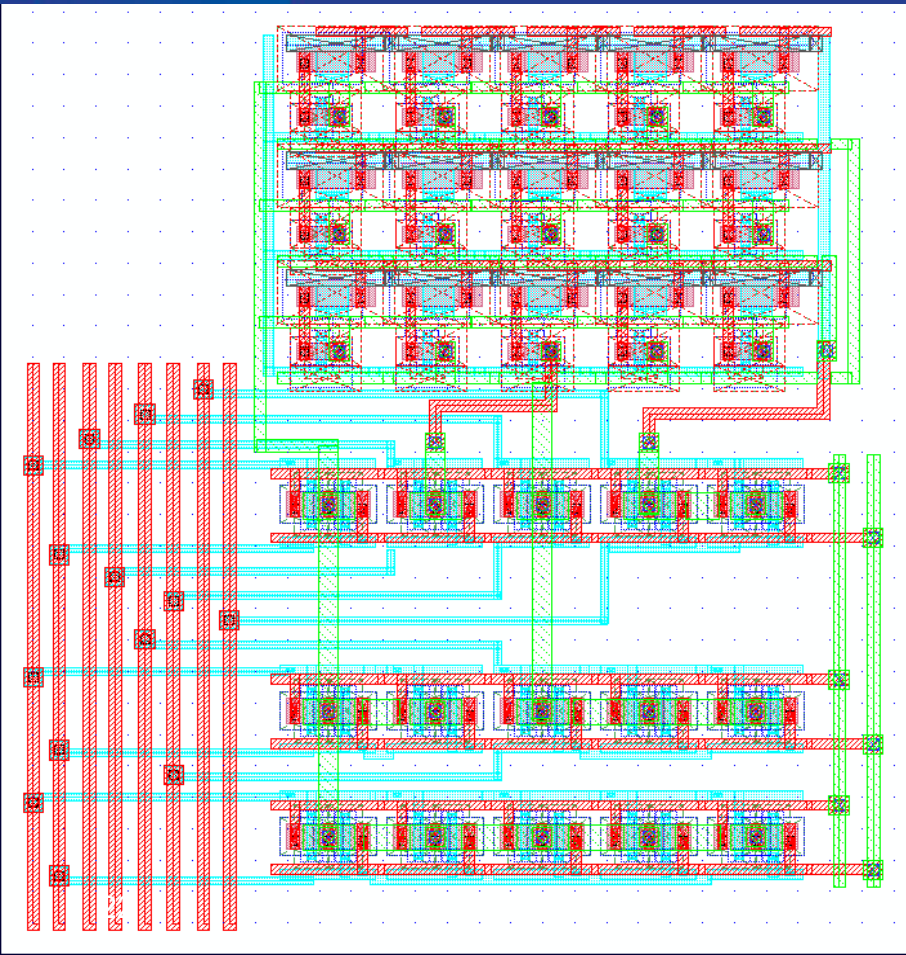


Current Steering DAC (4 bits)



- Binary weighted current mirrors
- Switches are also binary weighted
- Current can be steered either to positive or negative output

DAC Layout



4	3	4	3	4
4	2	1	2	4
4	3	4	3	4

Conventional symmetrical common centroid geometry for current mirrors
Helps to average out global errors

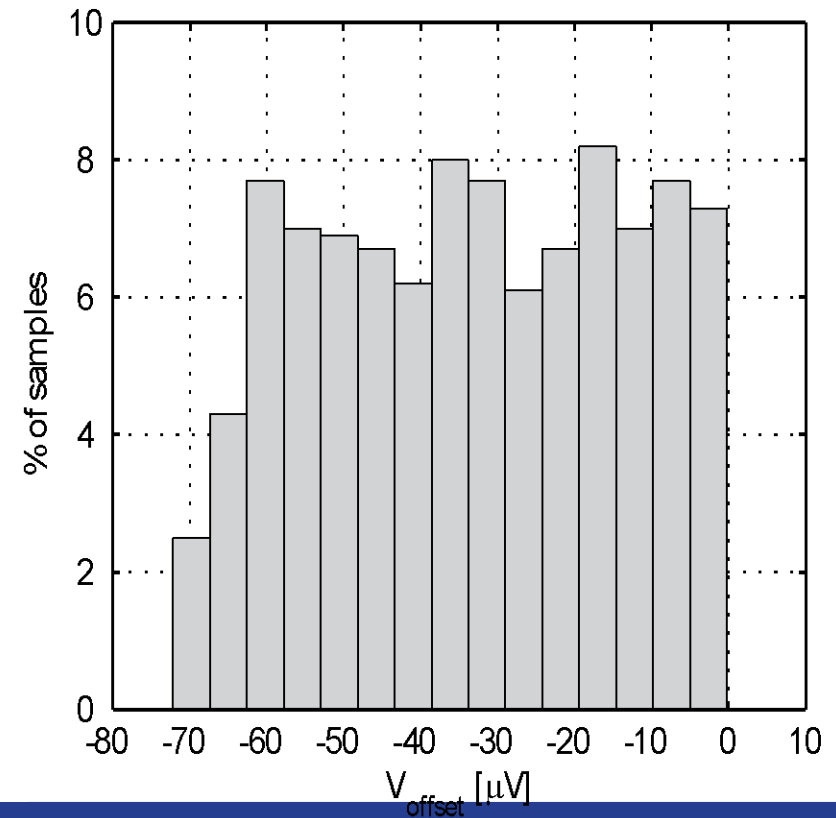
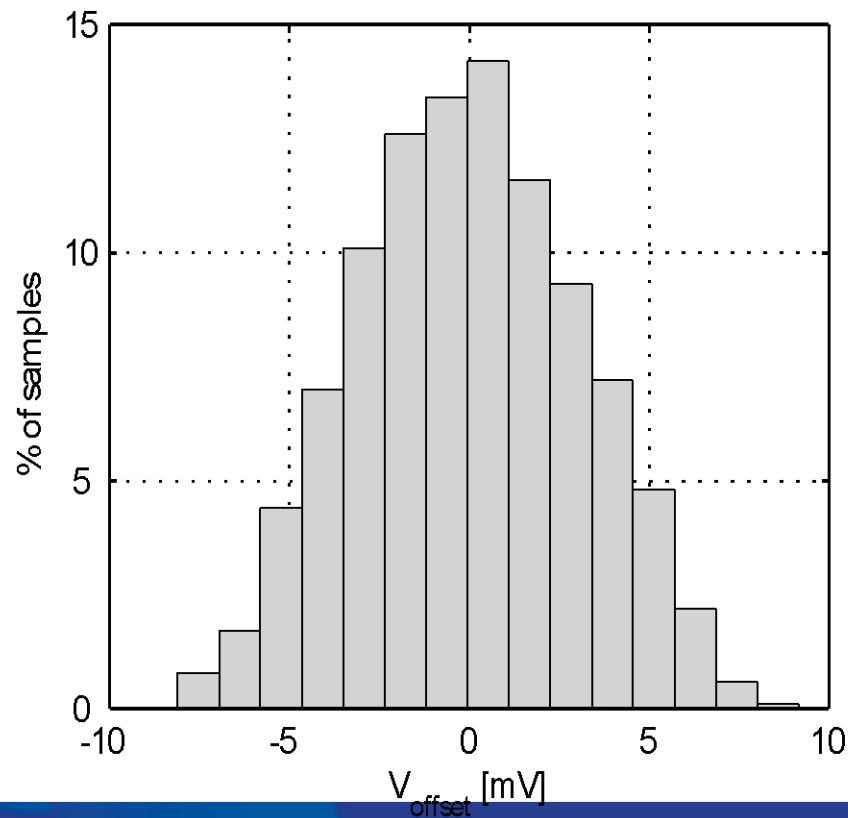
- Matching is critical for monotonic performance

Trimming DACs

Matching is expected to be worse for SOI, Data here corresponds to a typical bulk CMOS process

Offset distribution before compensation

Offset distribution after digital compensation



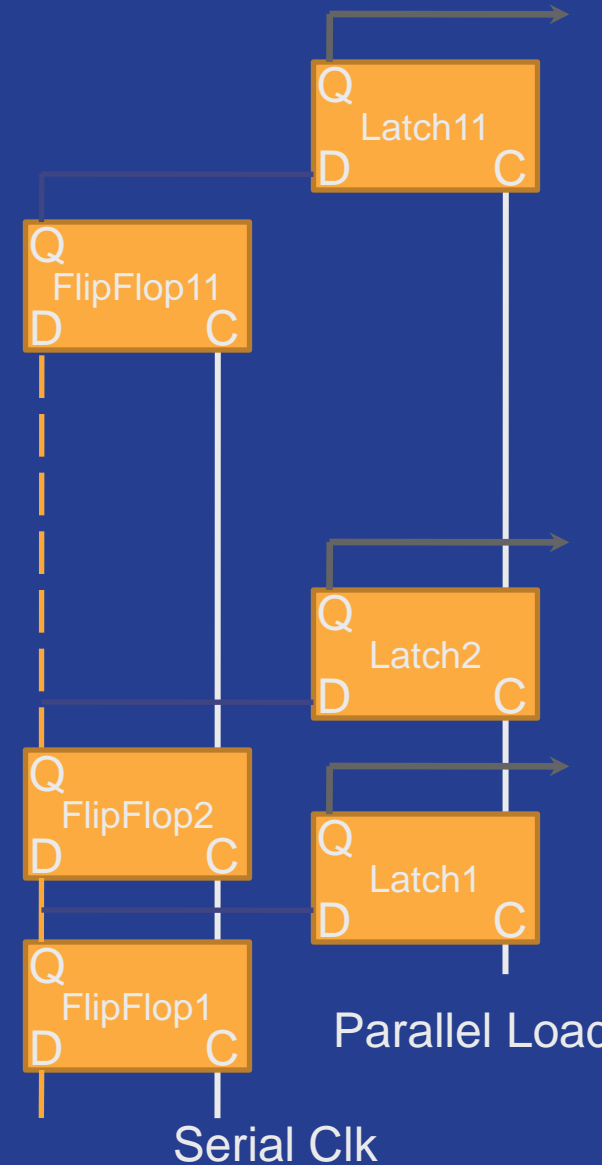
- Gaussian distribution
- Depends on component matching

- Uniform distribution
- Residual offset depends on DAC resolution

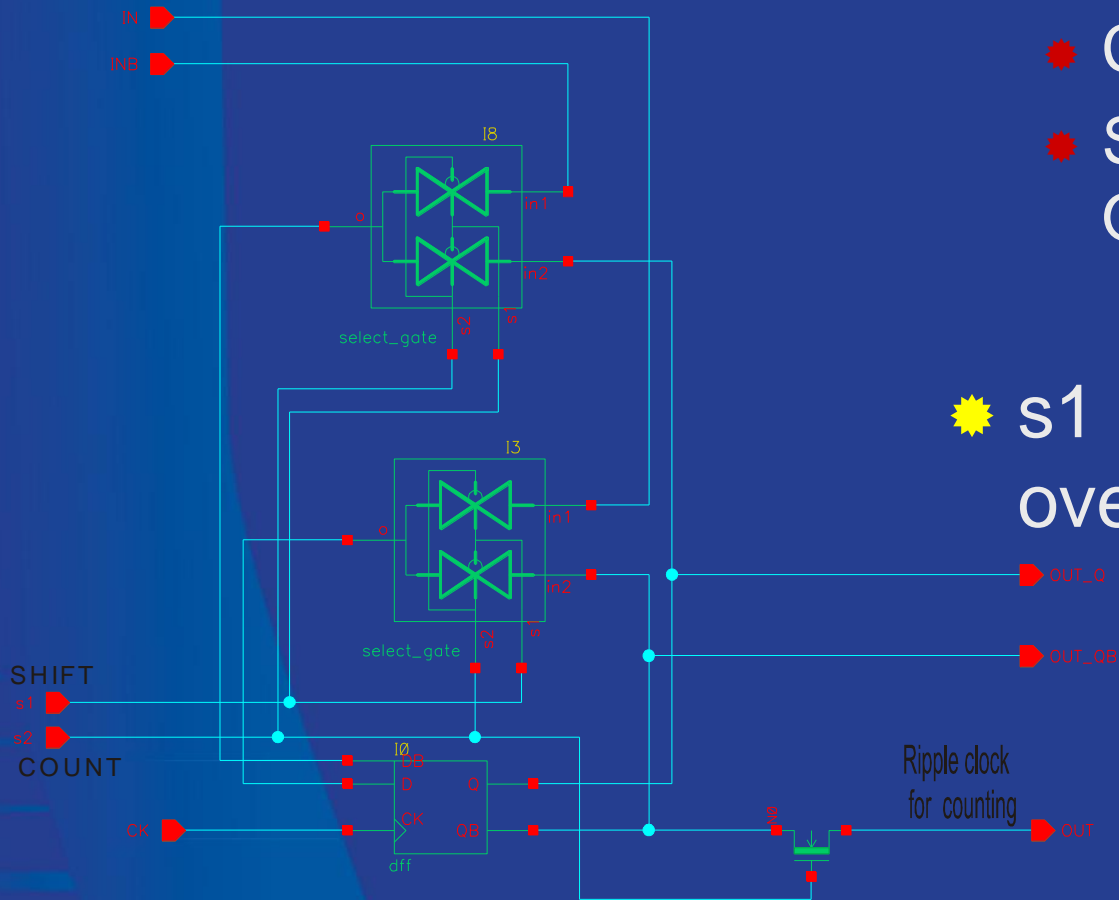
Configuration Register

- Serial In Parallel Load
- (4b x 2) for DAC settings
- 3 bit test setup
- Test Control block used as decoder to control switches for test

	Setup
000	Normal Operation
001	Analogue Output for test calibration
010	Test Input, counter connected
011	Calibrate DAC L
100	Calibrate DAC H
101	xx
110	xx
111	Pixel Disabled



1bit Counter

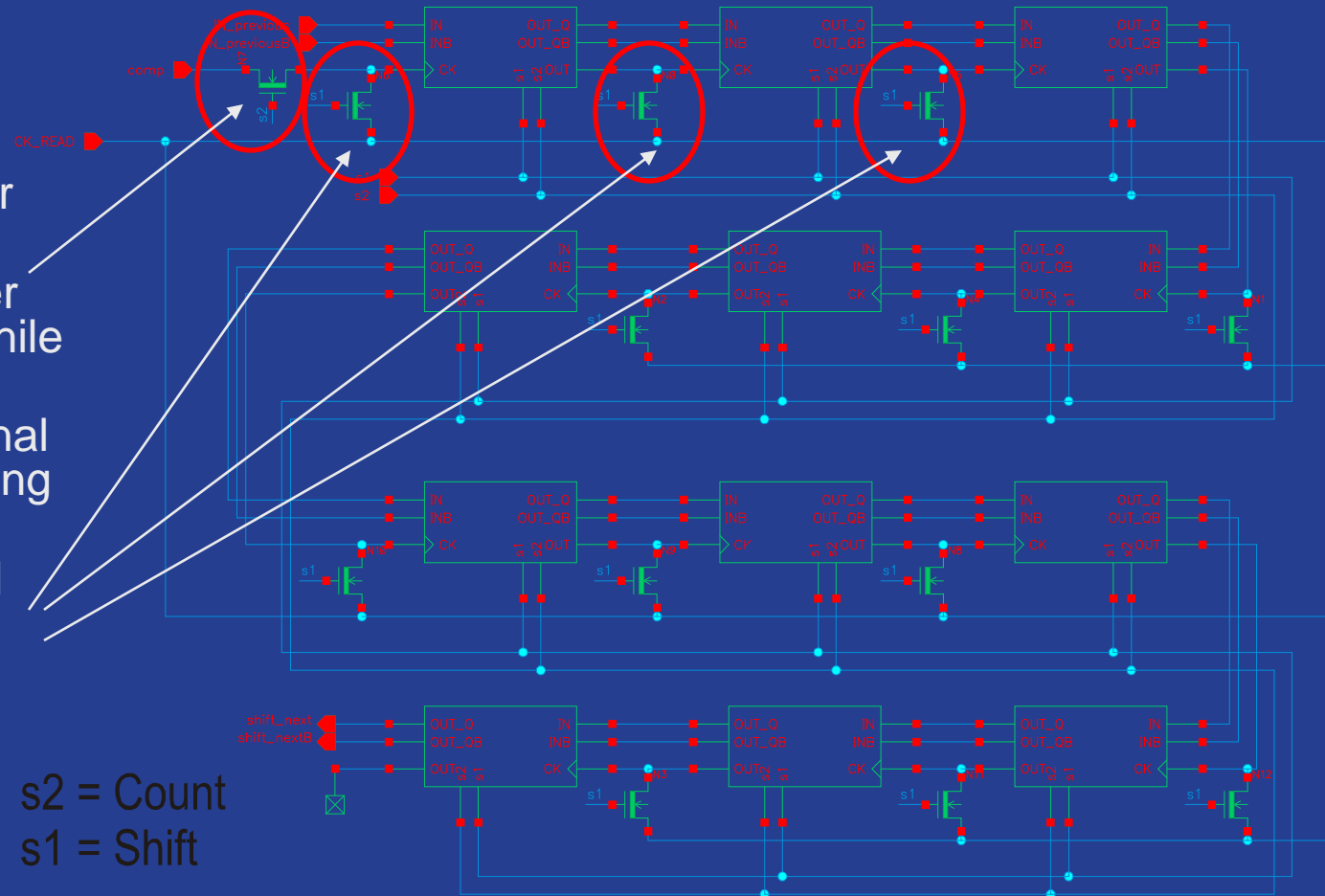


☀ Can be configured as:

- ☀ Counter (s1 is ON)
- ☀ Shift Register (s2 is ON)

☀ s1 and s2 are non-overlapping clocks

Counter /Shift Register



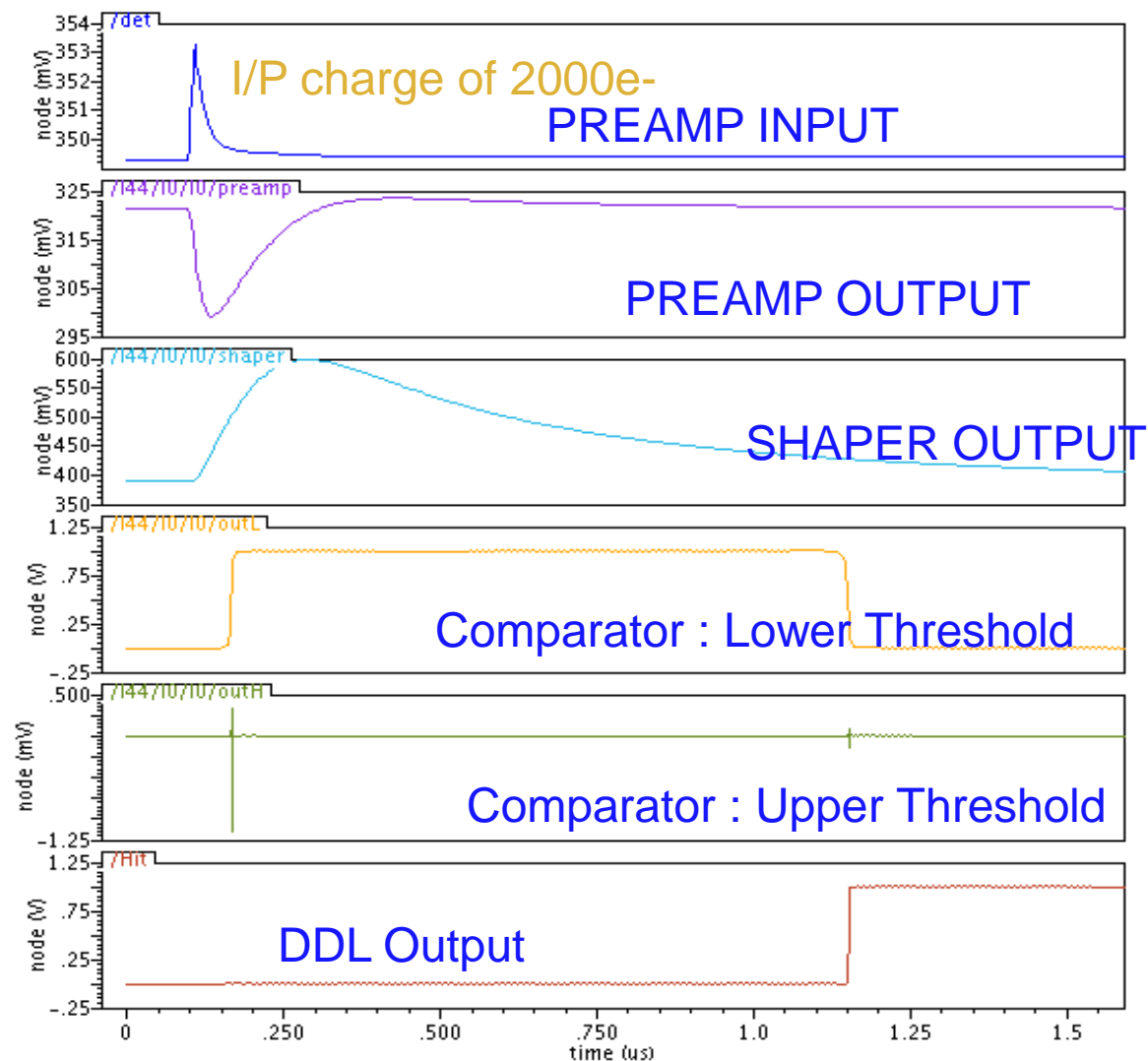
- 12 bit ripple counter
- Count switch disconnects counter from comparator while shifting
- CK_READ is external clock used for shifting data
- Shift switch applied shifting clock

s2 = Count
s1 = Shift

- s1 and s2 are non-overlapping clocks

Simulation result

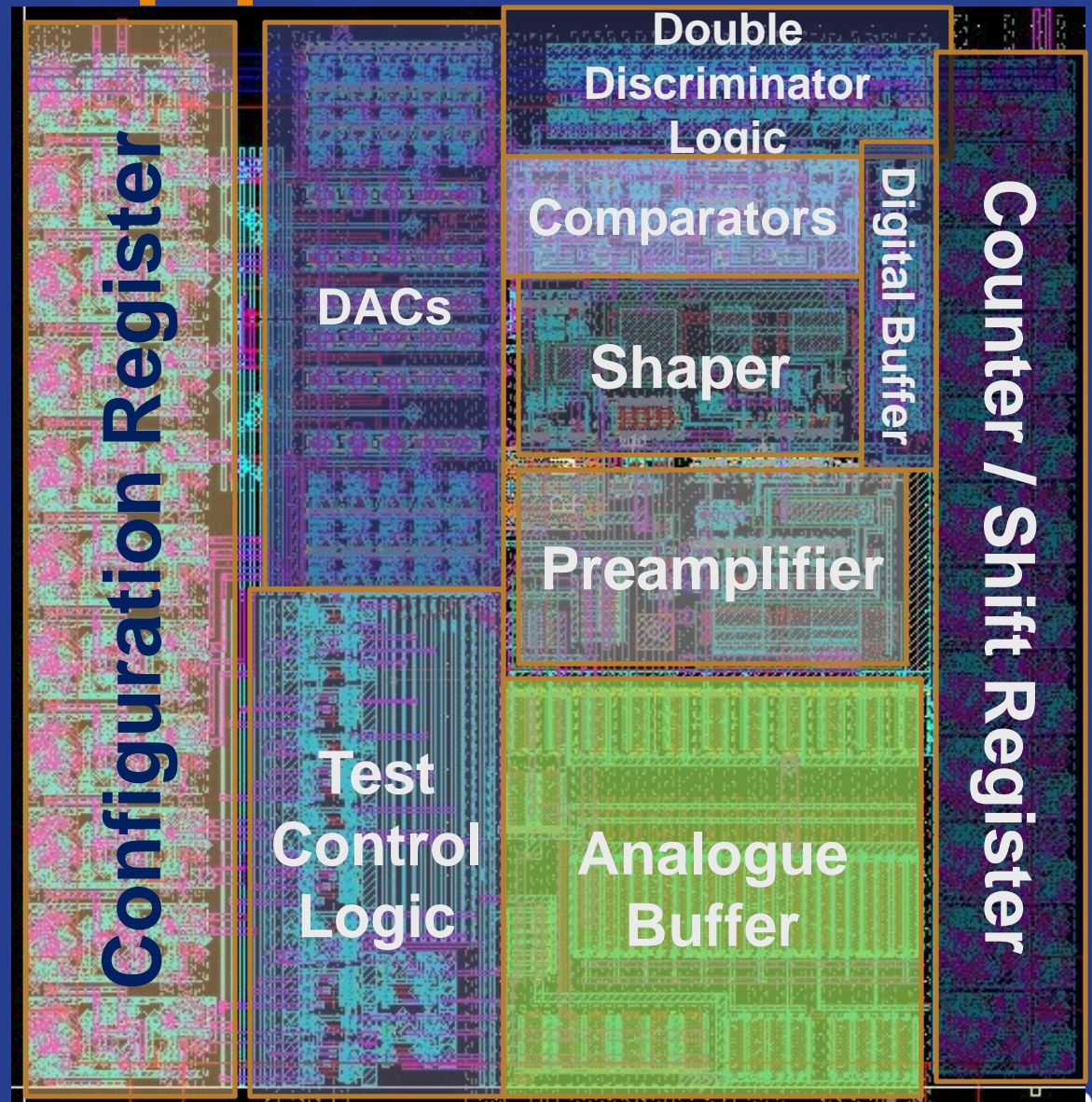
Transient Response



LAYOUT

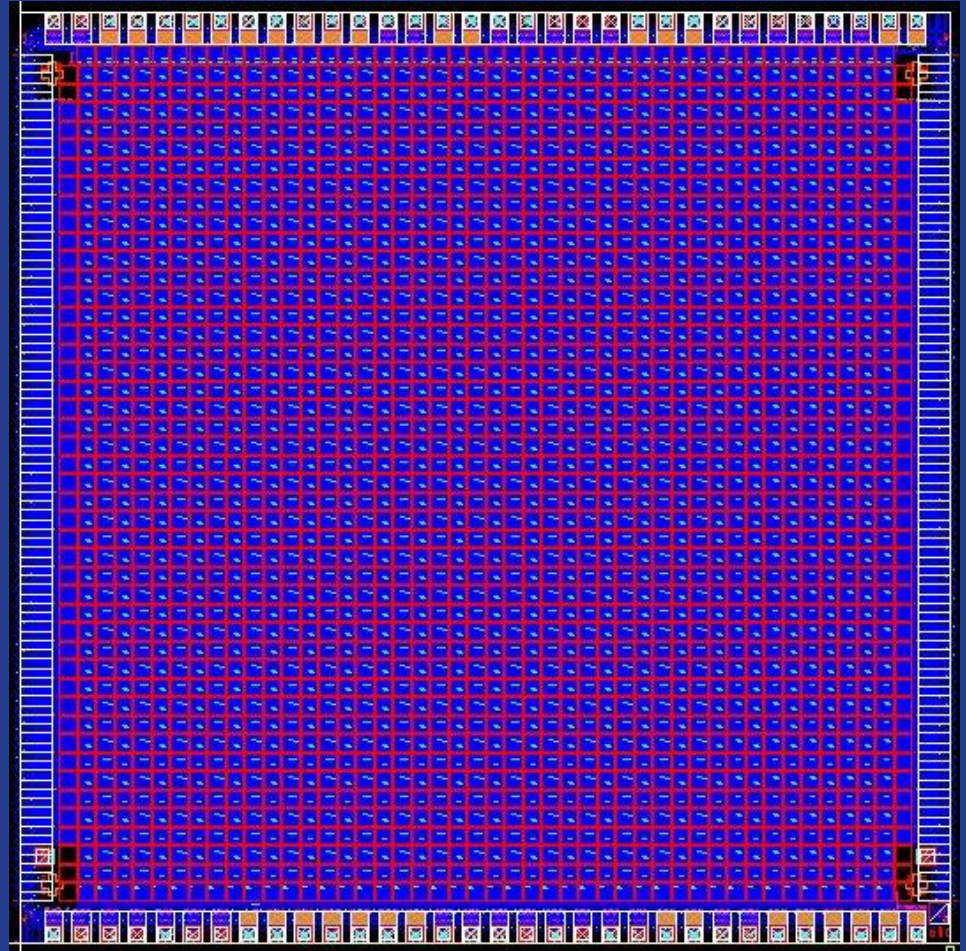
MAMBO3: top pixel

- $100\mu \times 100\mu\text{m}$
- Transistor count ~ 950
- Analogue and Digital buffers only active during single pixel test

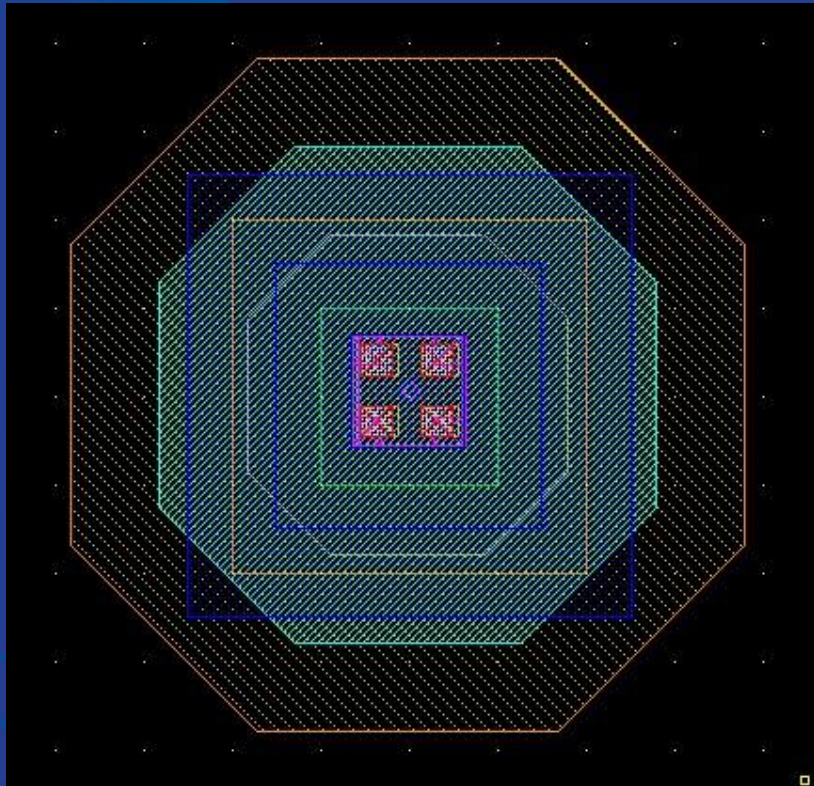


Upper Chip

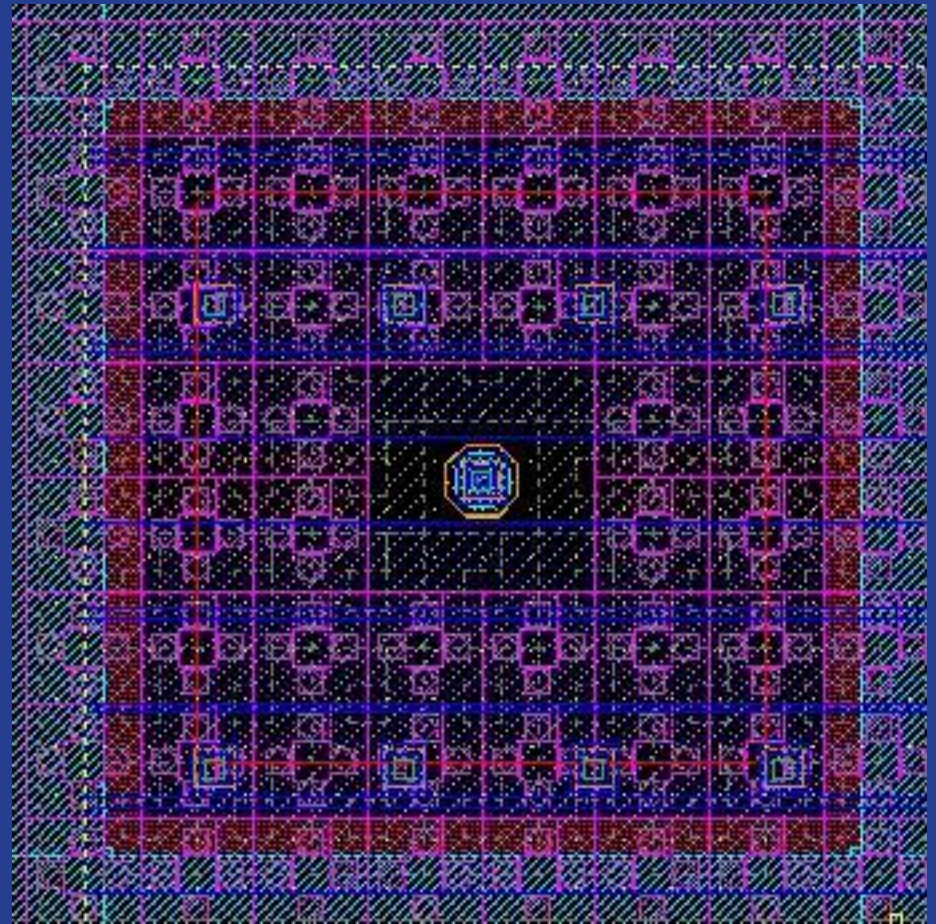
- 5mm x 5mm
- 1936 pixel matrix (44 x44)
- Each column has additional buffering of analog and digital signals
- Pads with back metal opening
- Alignment markers on all 4 corners



Lower chip: Diode Pixel

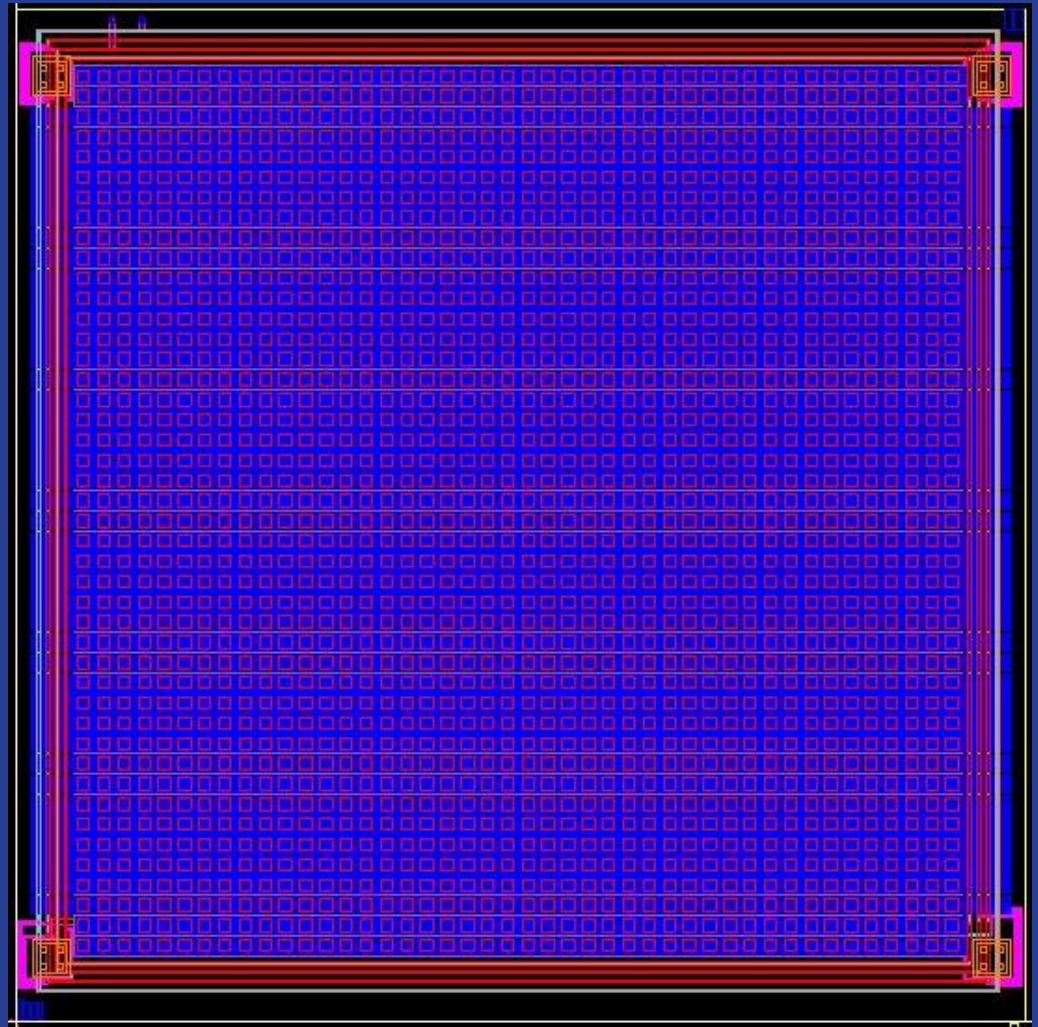
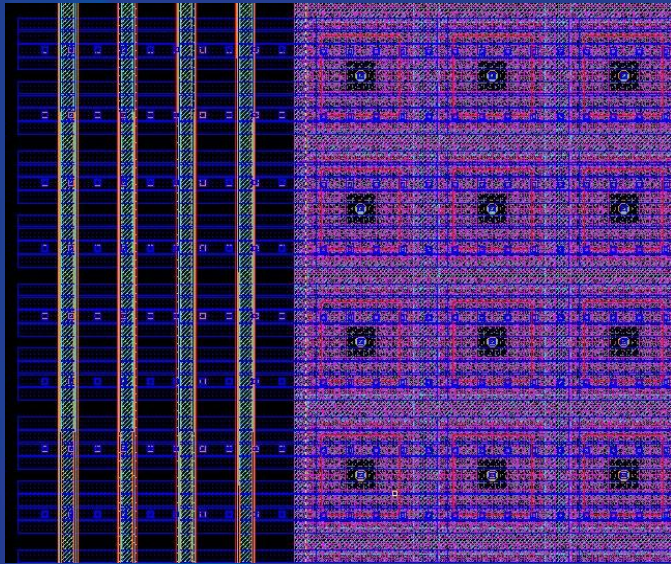


DIODE



100 μ x 100 μ

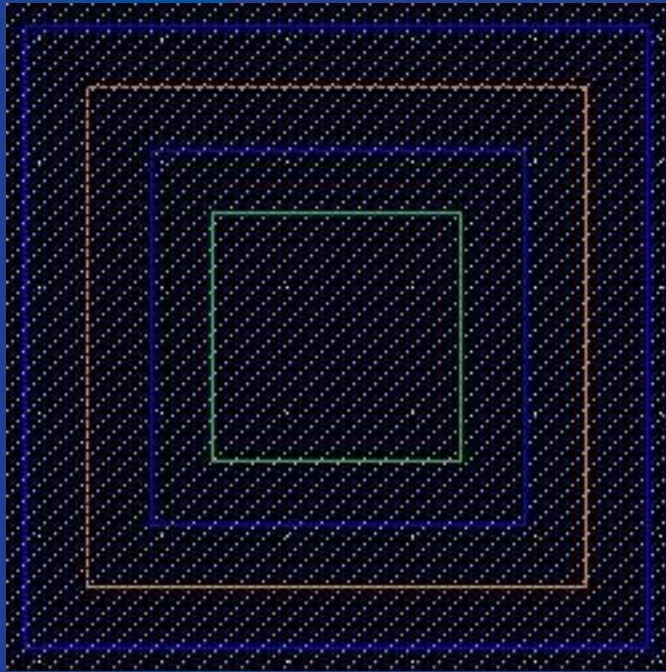
Lower Chip



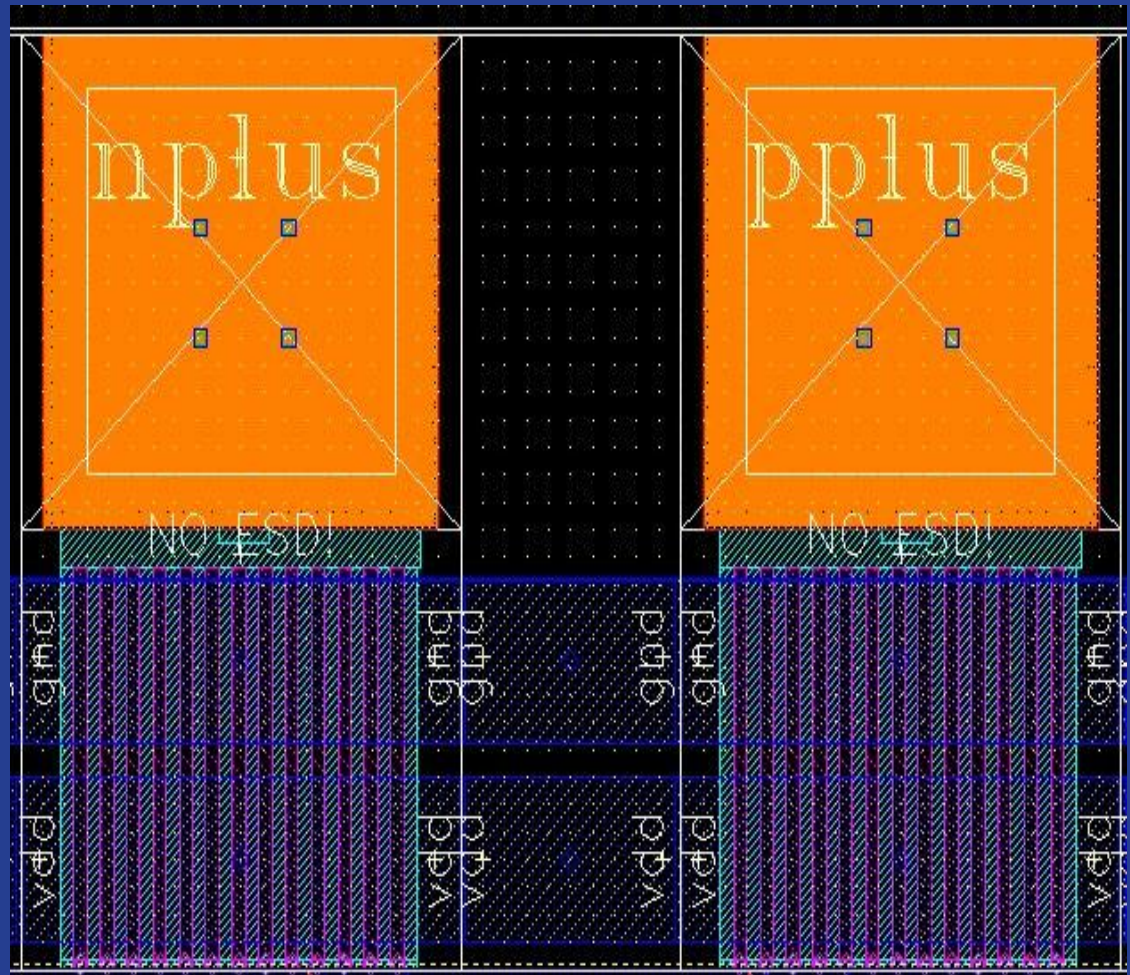
- 5mm x 5mm
- 1936 pixel matrix (44 x44)
- 4 guard rings around the matrix
- No bond Pads contains only micro bump pads, aligned with the top chip.
- Alignment markers on all 4 corners

Chip connection

MICROBUMP (5 μm x5 μm)

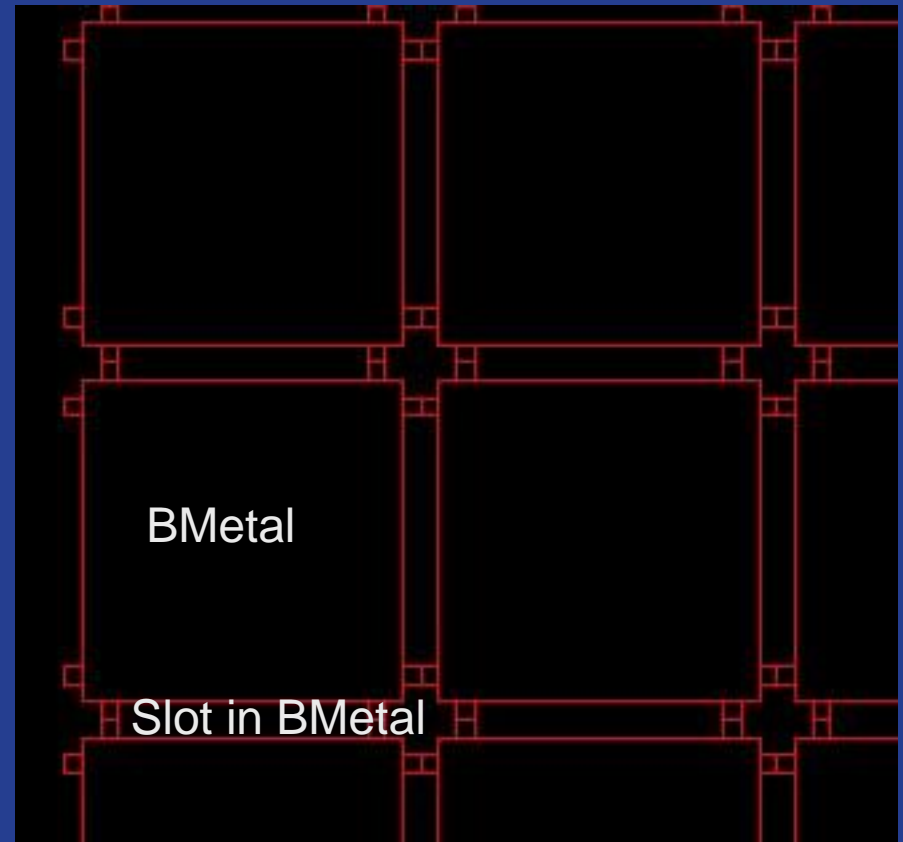


- Diode connection per pixel
- Dummy connections
- guard rings
- diode shielding (gnd!)
- gate control

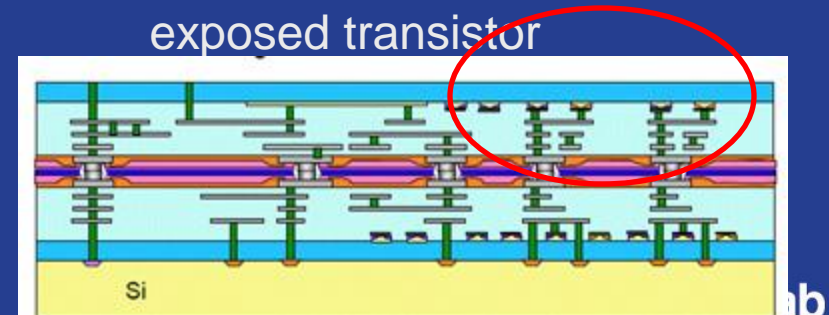


Protection

- After handle wafer is removed the bodies of transistors and sensitive nodes are exposed to electrical coupling from external environment
- Backplane connected to Analogue Ground per pixel
- Peripheral digital logic connected to Digital ground plane

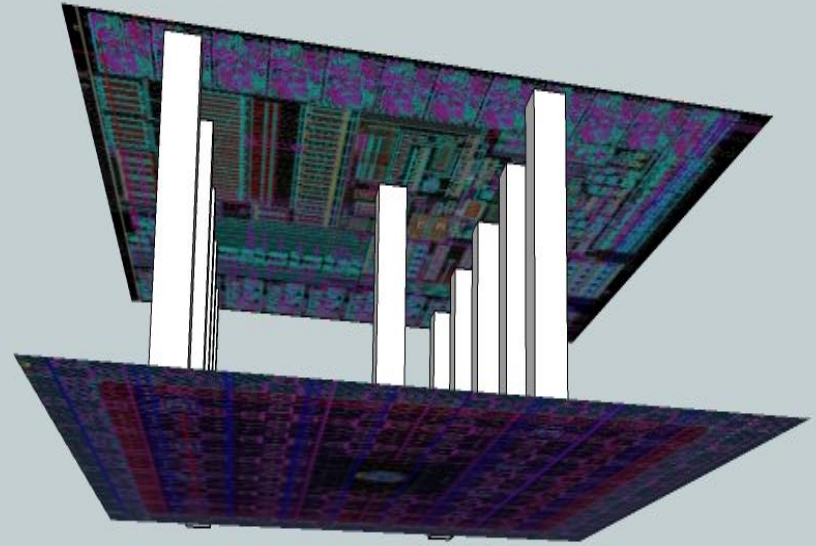
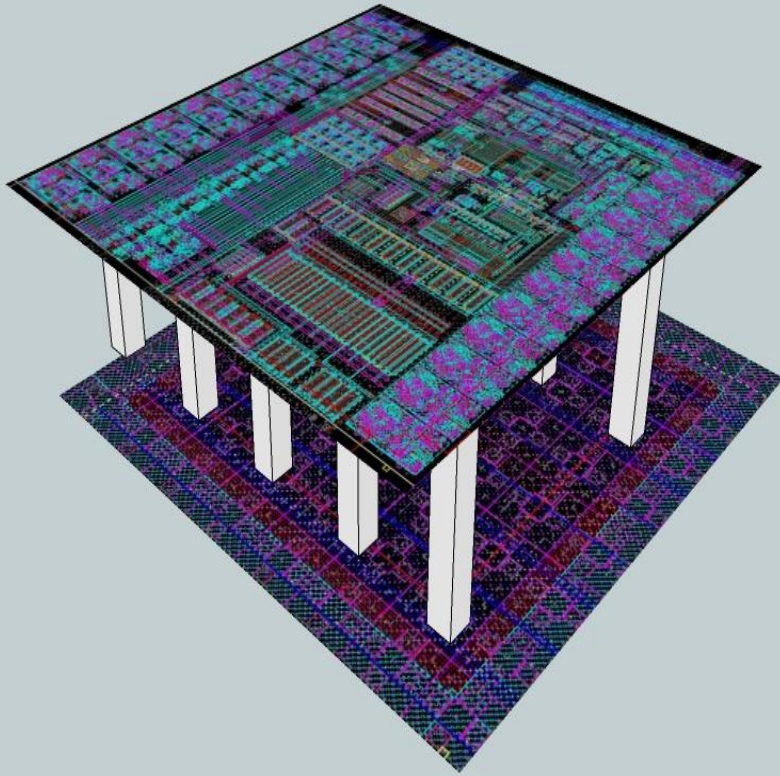


Shielding per pixel using back metal



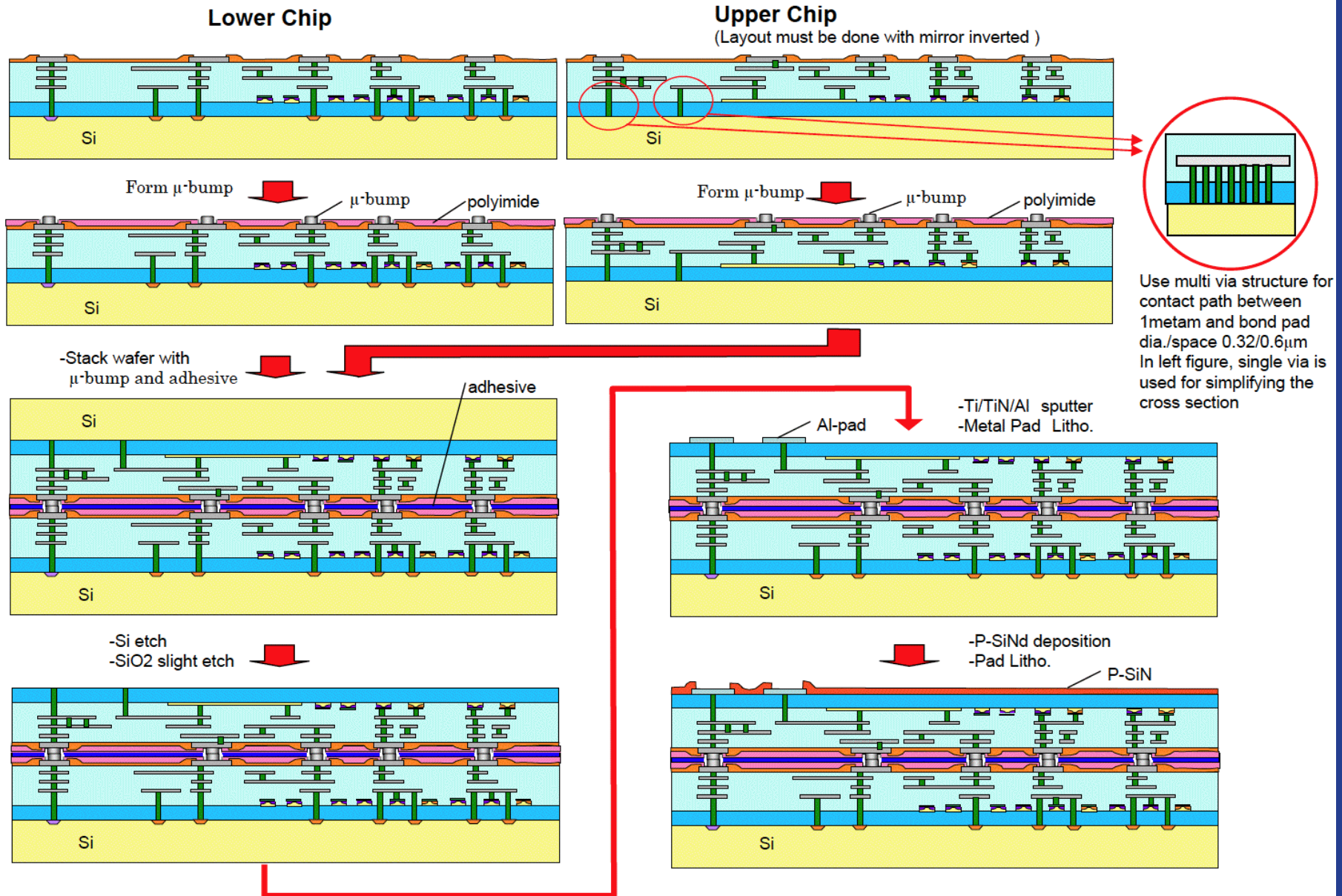
INTEGRATION

3D Model

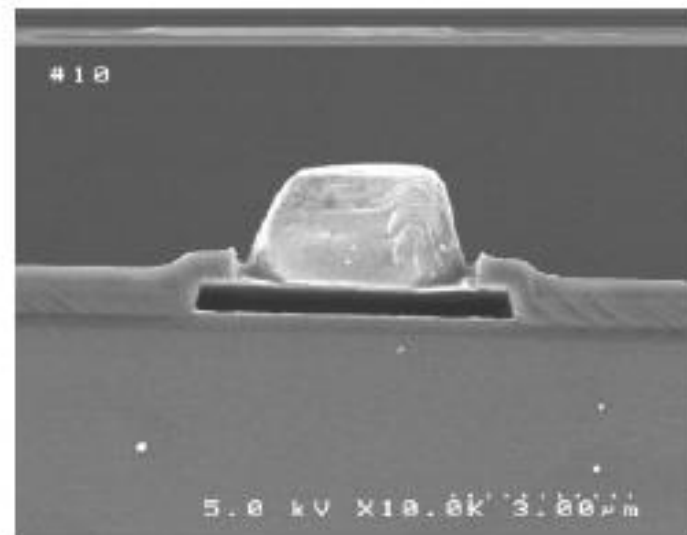
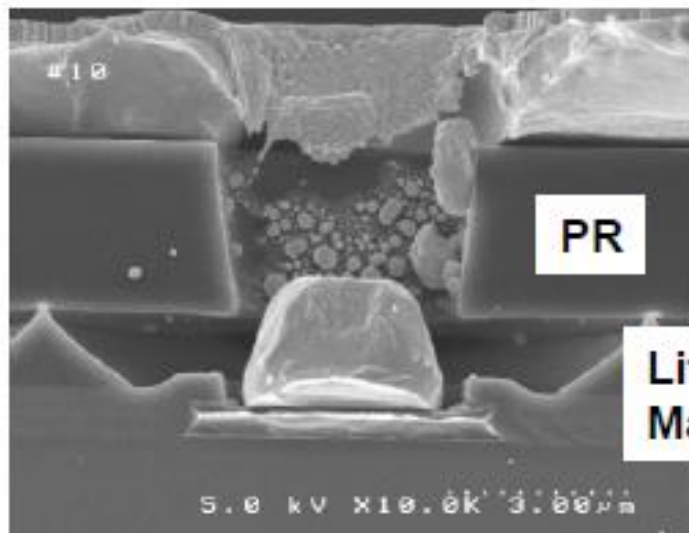
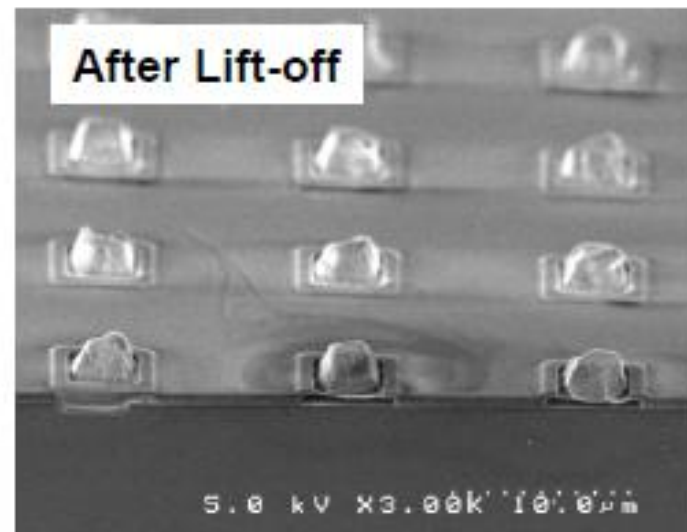
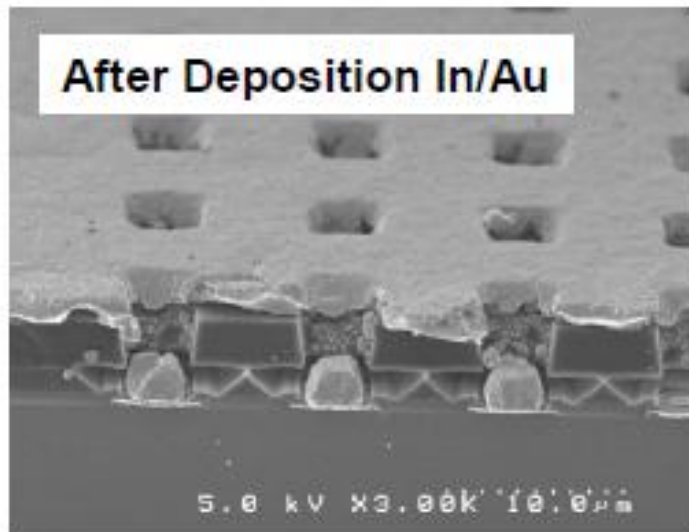


T-Micro 3D Integration process

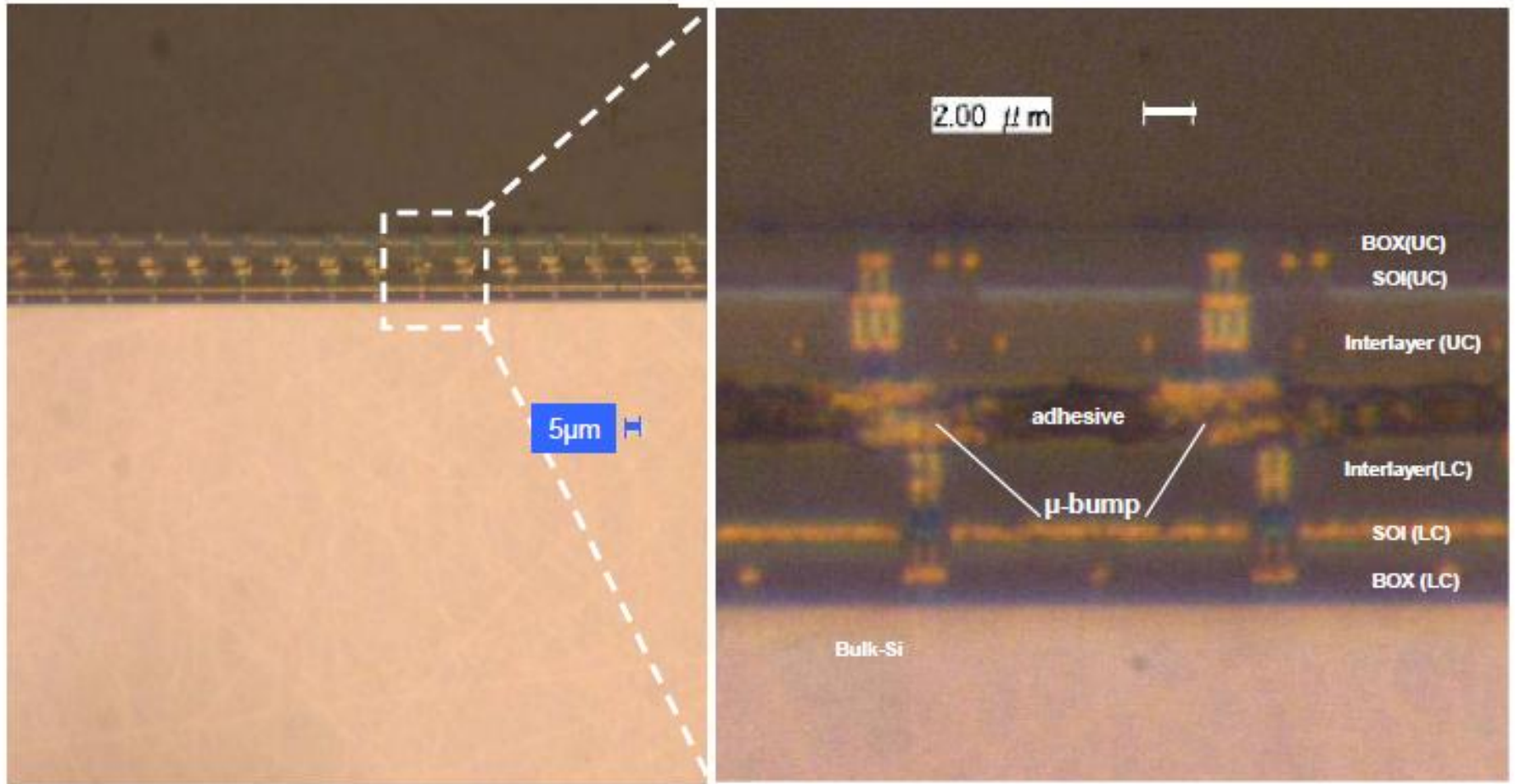
(1) Stack Process Flow (after finishing wafer process)



μ -bump process



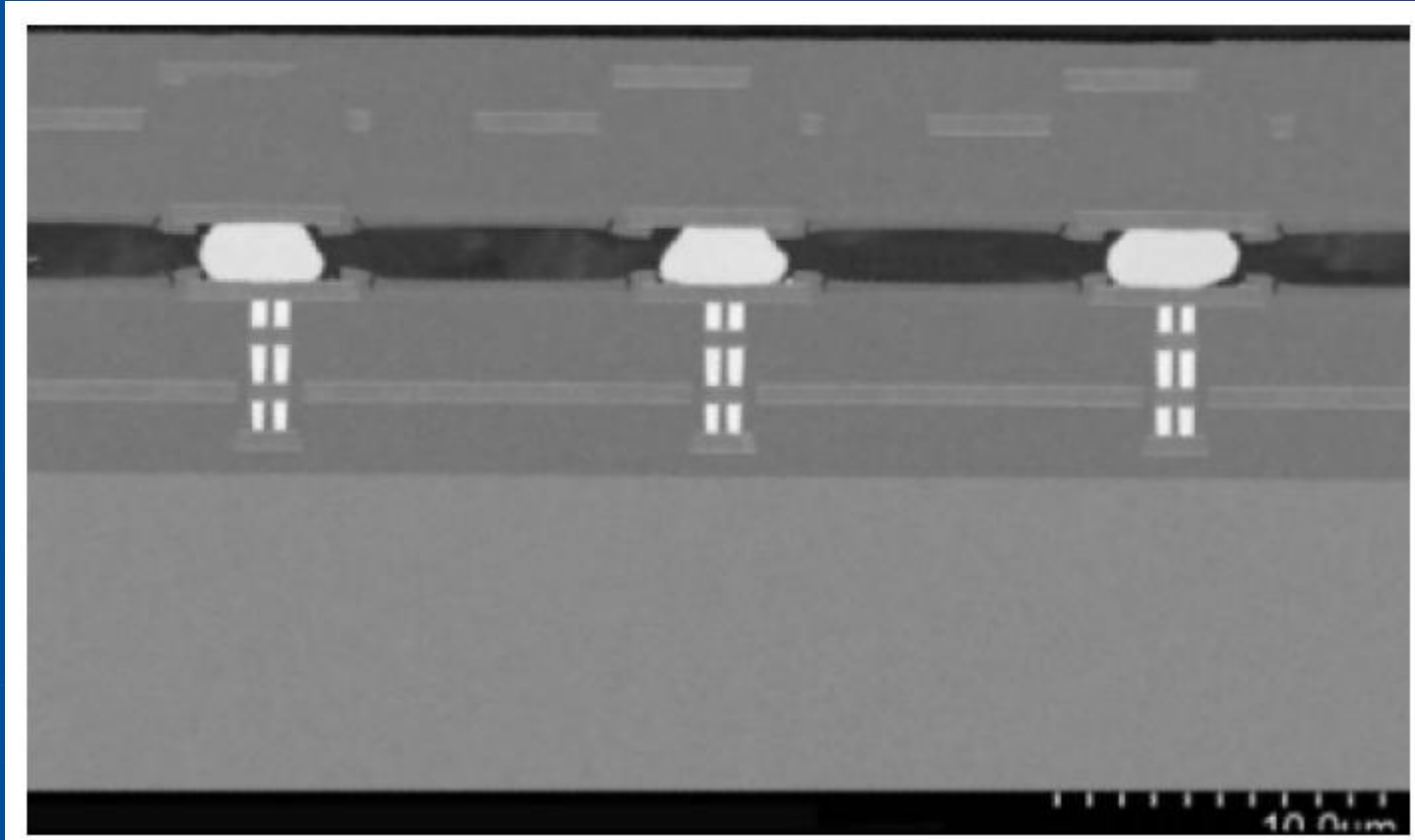
Cross sectional view



Tohoku Univ. / T-Micro

Cross sectional view:

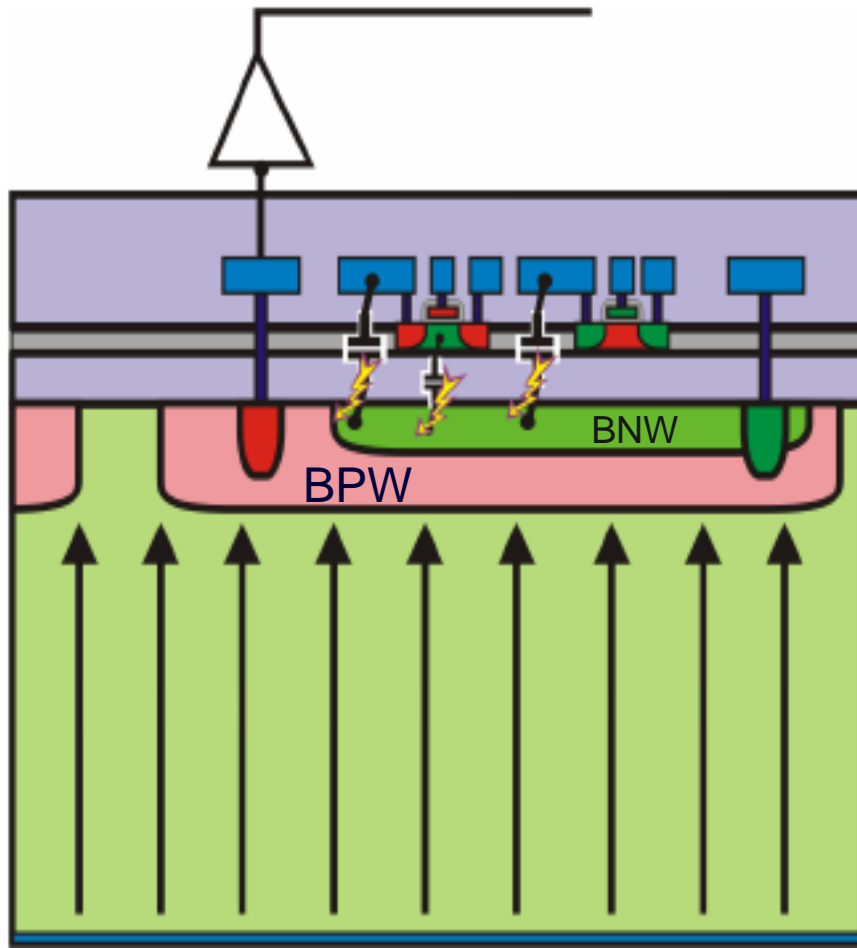
Test chip with adhesive



© T-Micro , VIPS 2010

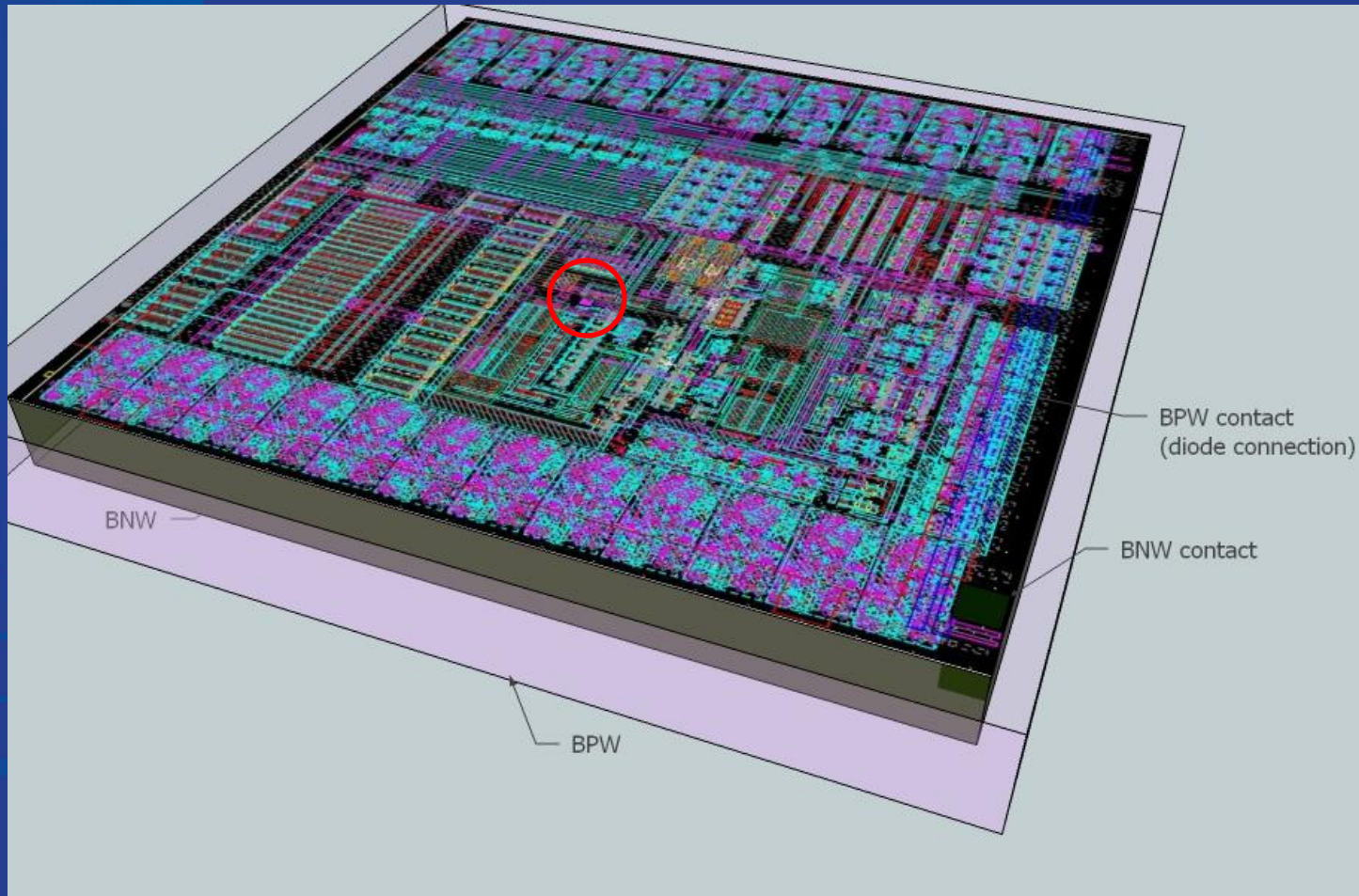
MAMBO IV: FUTURE WORK

Back to 2D

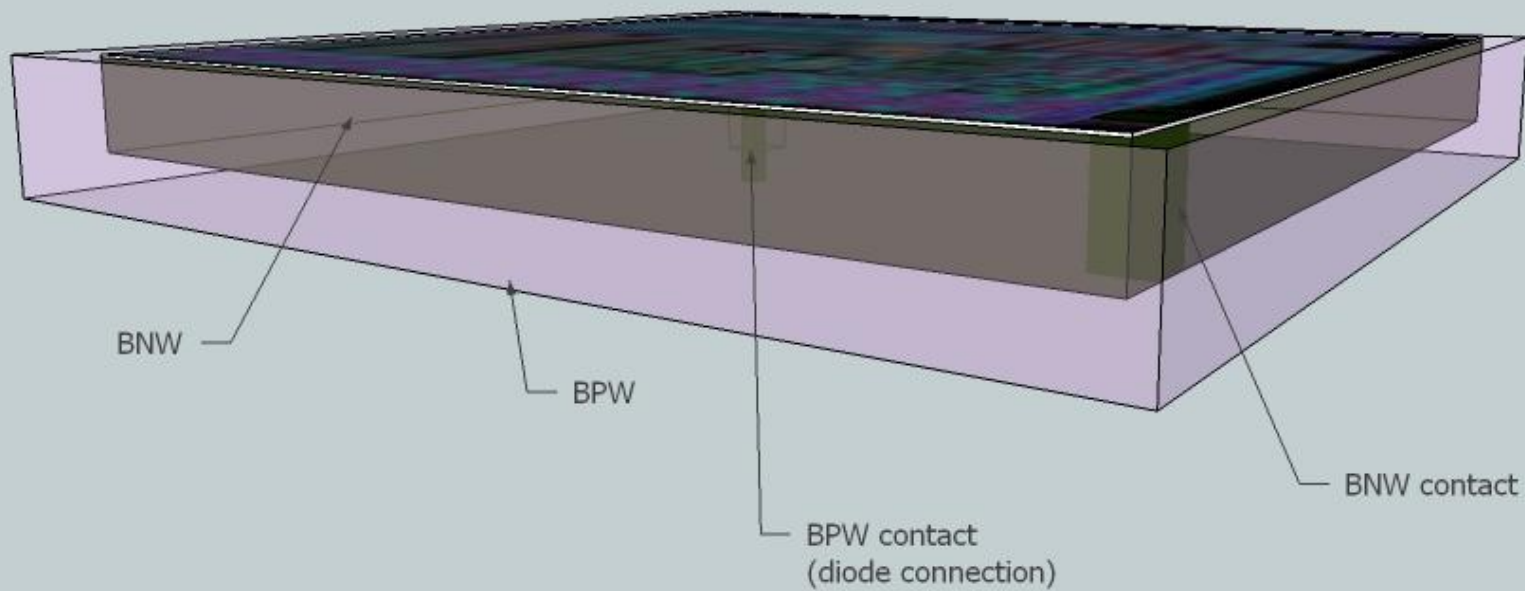


- ✦ Availability of nested well option
- ✦ BNW layer inside a deeper BPW implant
- ✦ Isolation of diode and electronics
- ✦ Increased parasitic junction capacitance (currently undetermined)

MAMBO IV



MAMBO IV



Thank you